

# Nano-carbon structures for electronic applications?

1<sup>st</sup> Ireland SummerSchool 2011

Georg S. Duesberg  
School of Chemistry Trinity College Dublin  
Dublin 2, Ireland

Centre for Research on Adaptive Nanostructures and  
Nanodevices  
(CRANN)



# Outline

---

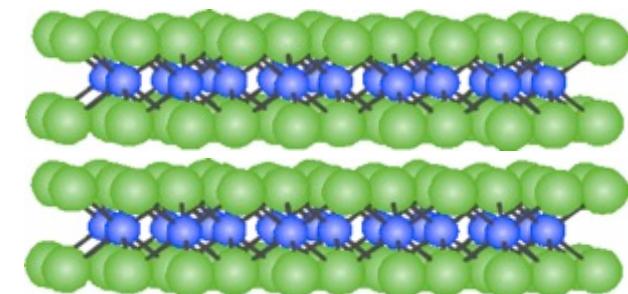
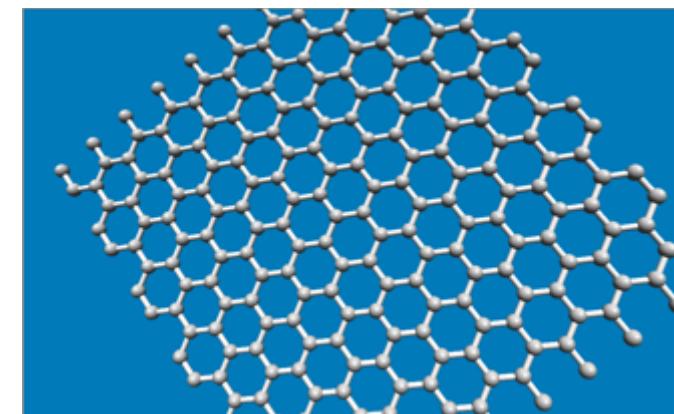
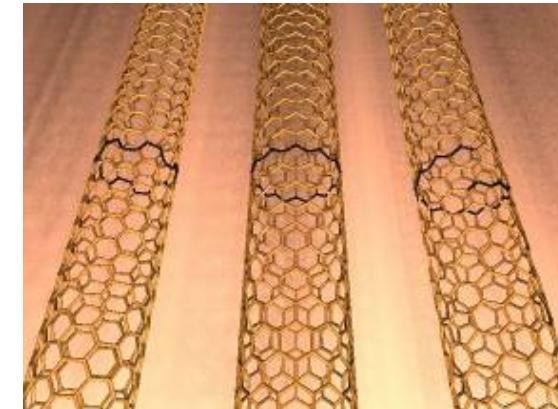


- ▶ Carbon Nano-structures: Applications in microelectronics
- ▶ Vertical Carbon devices
- ▶ Graphene Processing
- ▶ Other 2D Materials
- ▶ Carbon NEMS?
- ▶ Conclusions

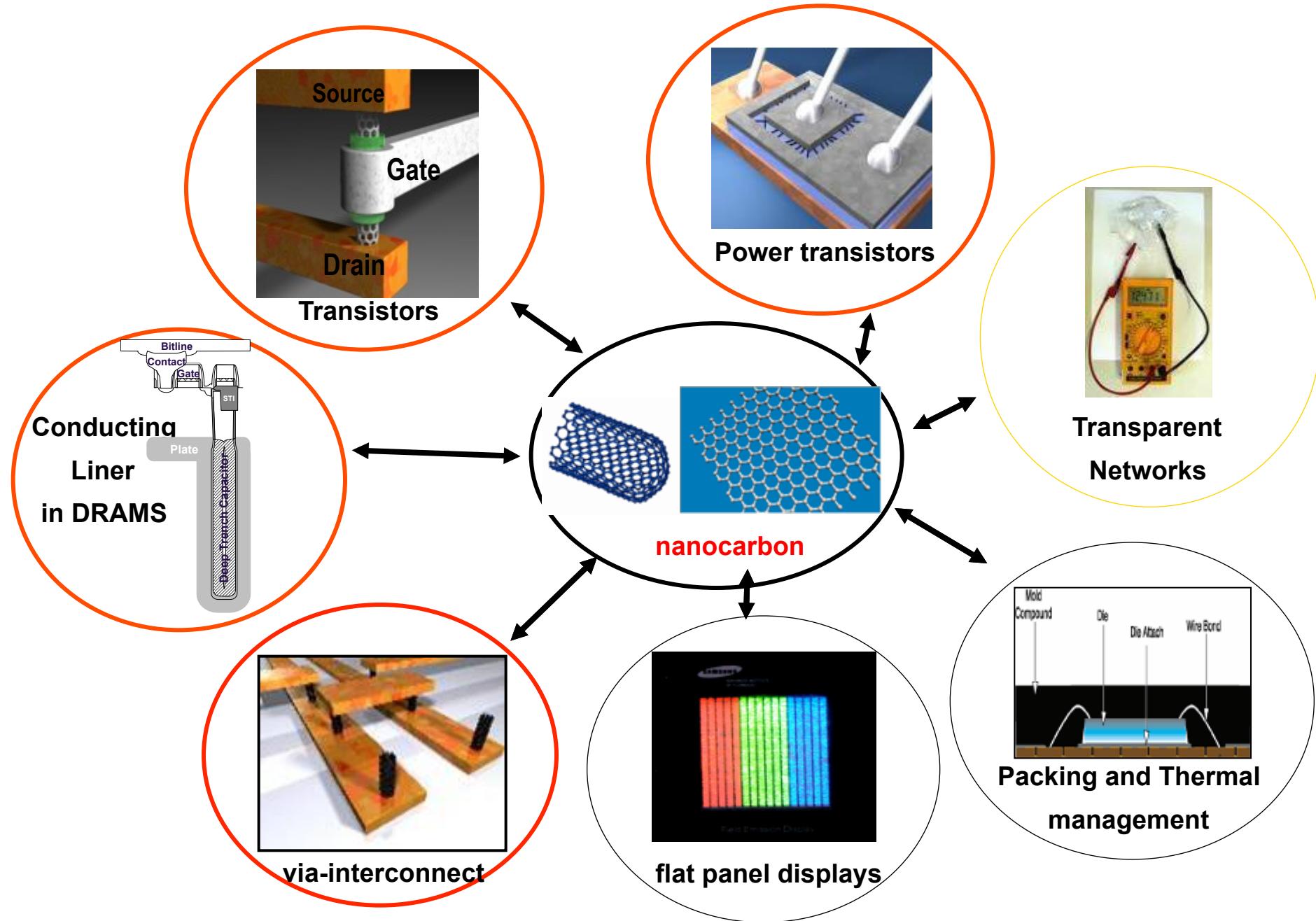


# Graphene and Nanotubes – Unique Properties

- High Mobilities – Ballistic conductance, massless Dirac fermions in graphene
- High Thermal Conductivity
- Room Temperature Quantum Effects
- Tuneable Band Gaps
- High surface area
- Chemically inert
- Mechanically stable

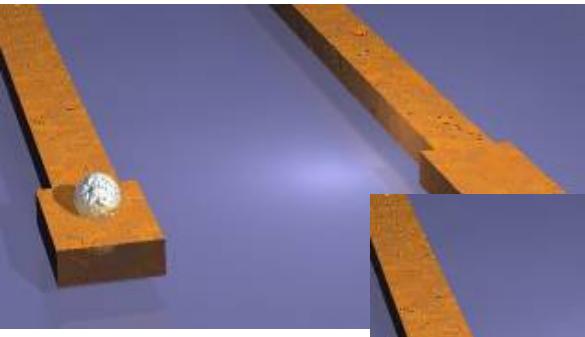


# Potential Applications for Carbon Nanostructures in electronics

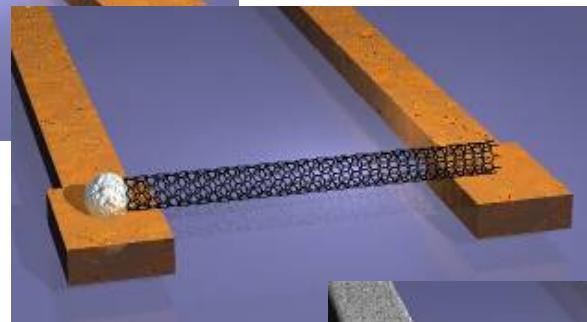




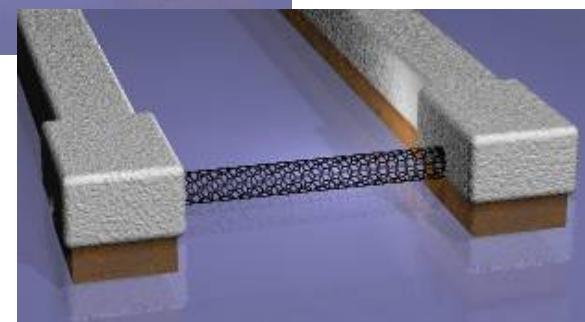
# Lateral CNTFETs – process flow



Structure metal contacts and Catalyst on wafer scale

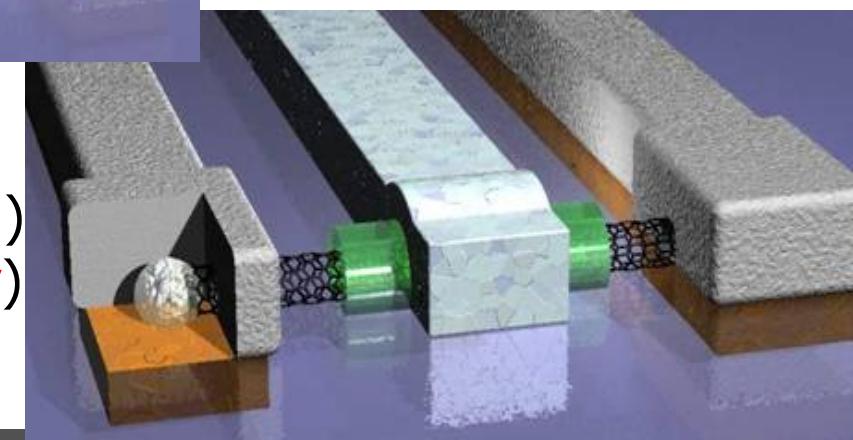


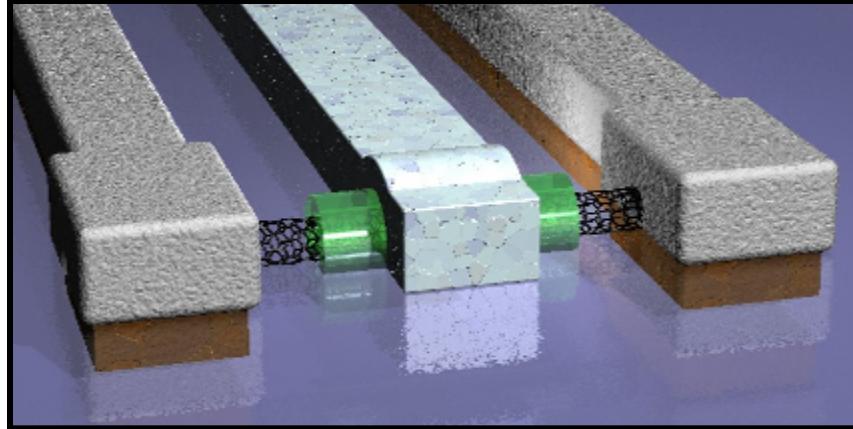
Deposition by drop casting  
or CVD – **random process!**



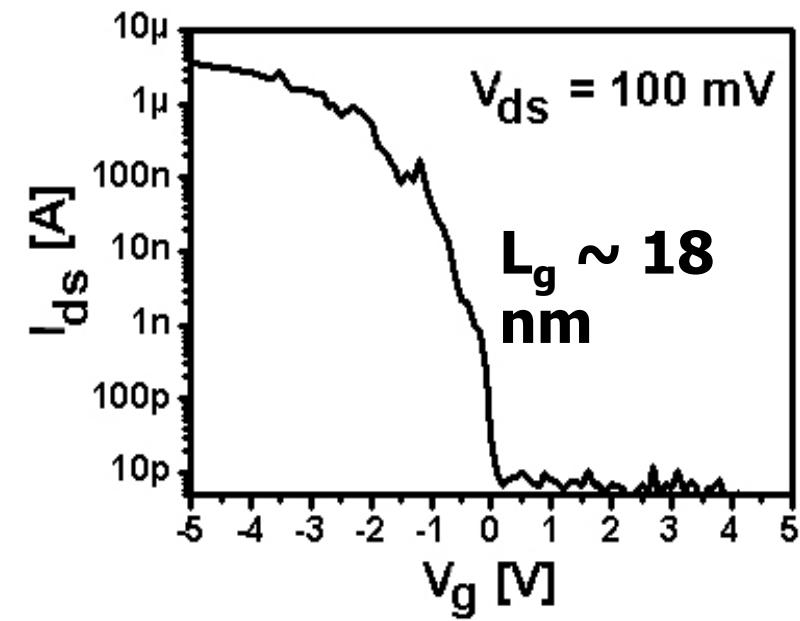
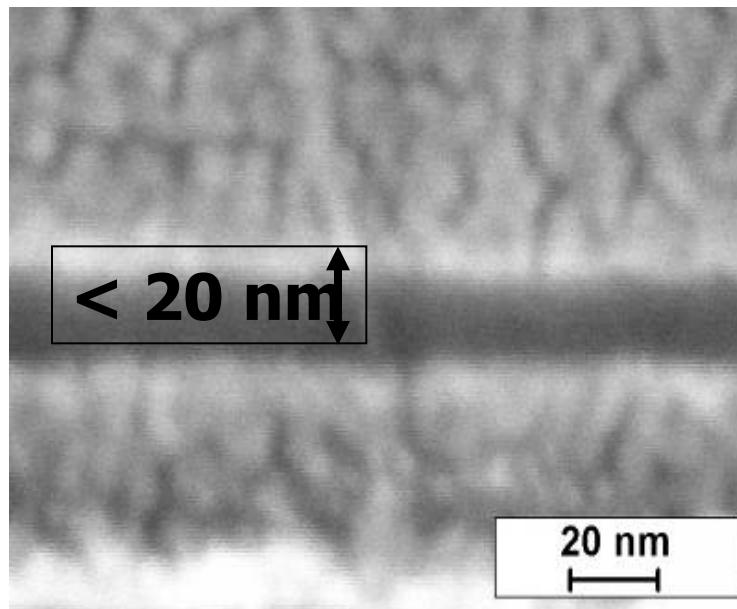
Encapsulate CNT and  
Contact by electroless  
deposition

Apply Dielectric (Dip Coat Process!)  
and Top Gate (**E-beam lithography**)



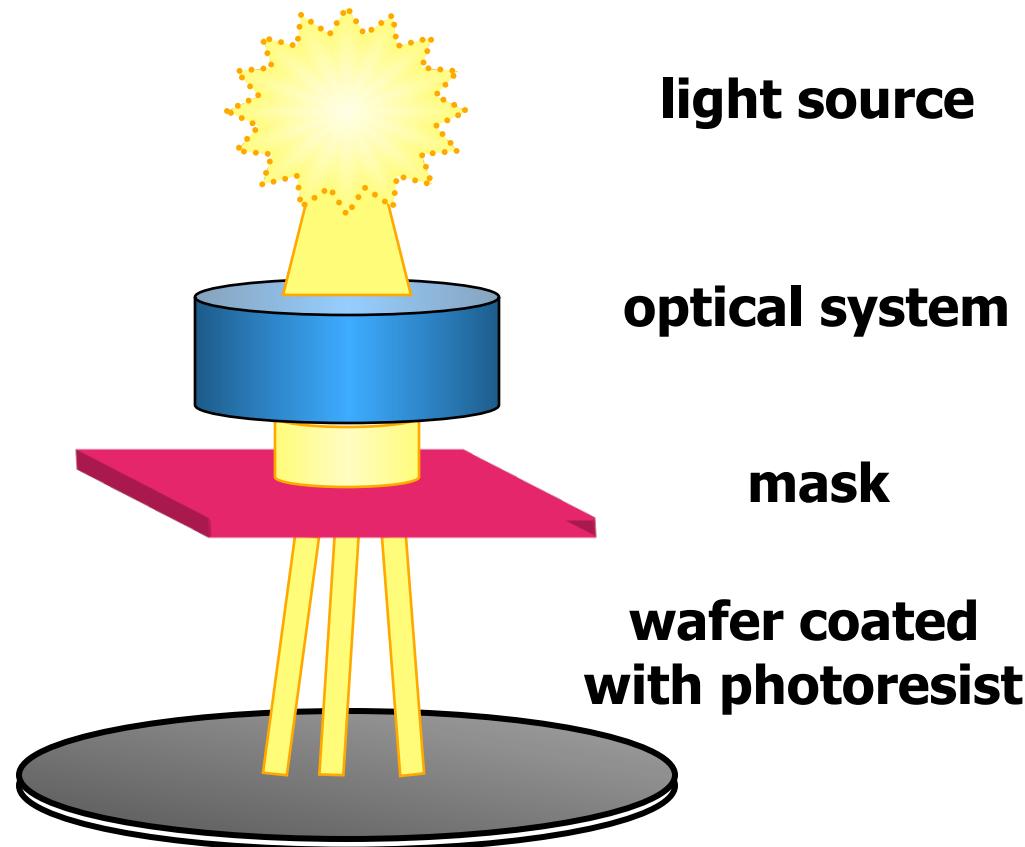


- ⇒ Works at channels shorter than 20 nm!
- ⇒ Ballistic regime
- ⇒ Ultra high currents can be switched ( $I_{on} > 10 \mu\text{A}/\text{tube}$ )
- ⇒ On/off ratio  $> 10^5$





# Power of silicon processing and lithography



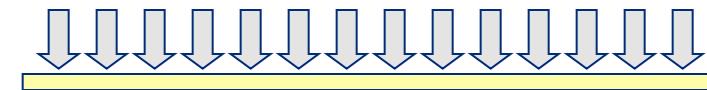
**light source**

**optical system**

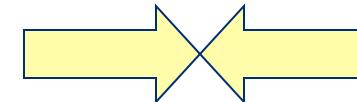
**mask**

**wafer coated  
with photoresist**

Parallel Processing

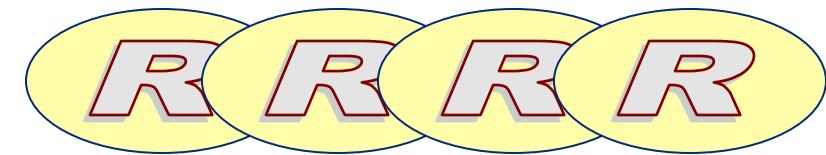


Lateral Scaling



Reproducibility

*good process control high yield*

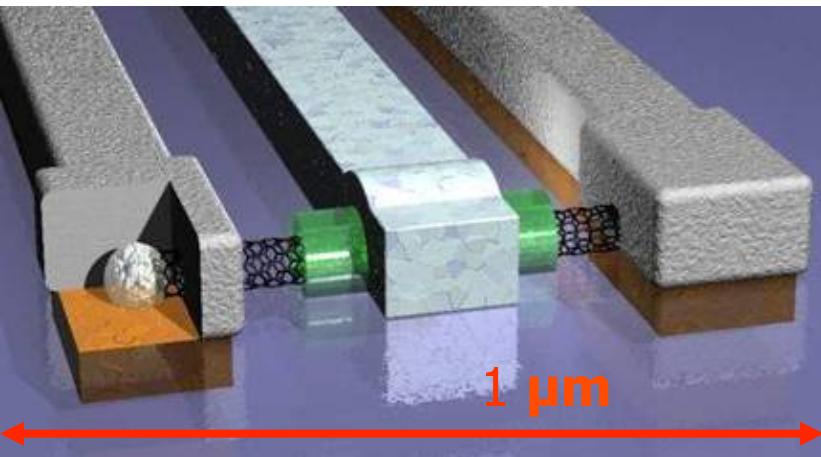


**Throughput –**

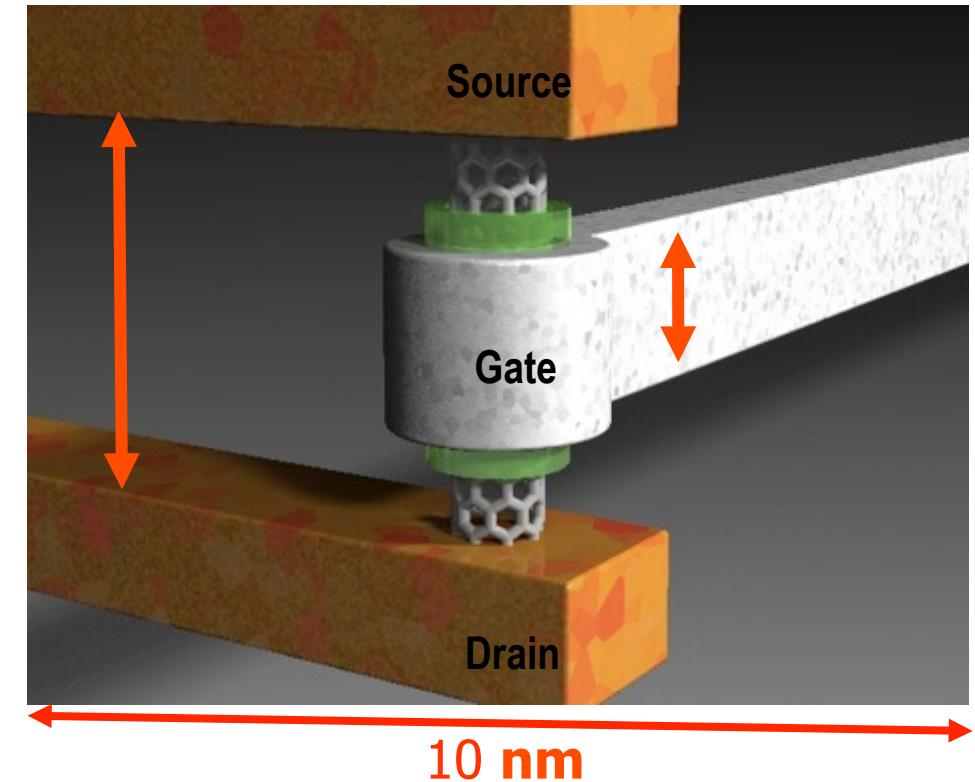
the number of wafers per hour optical lithography → **60 - 90** wafers/hour

# Limitations of lateral CNTFET approach

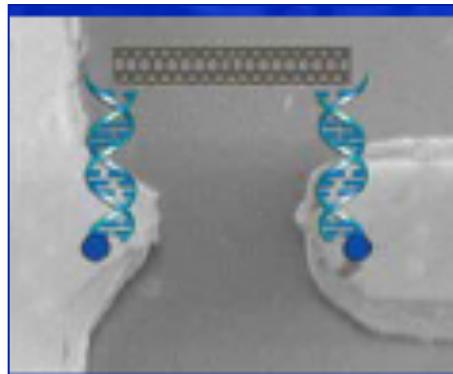
Lateral dimensions?



The vertical CNTFET could be the solution – but there is still a long way to go....

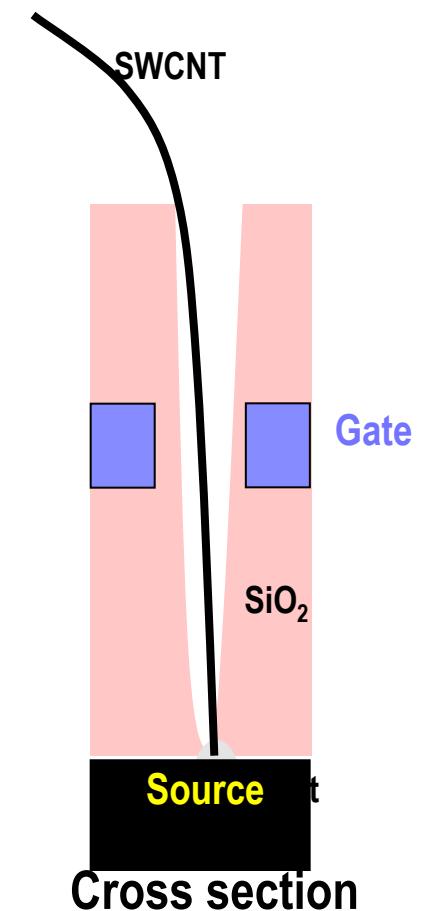
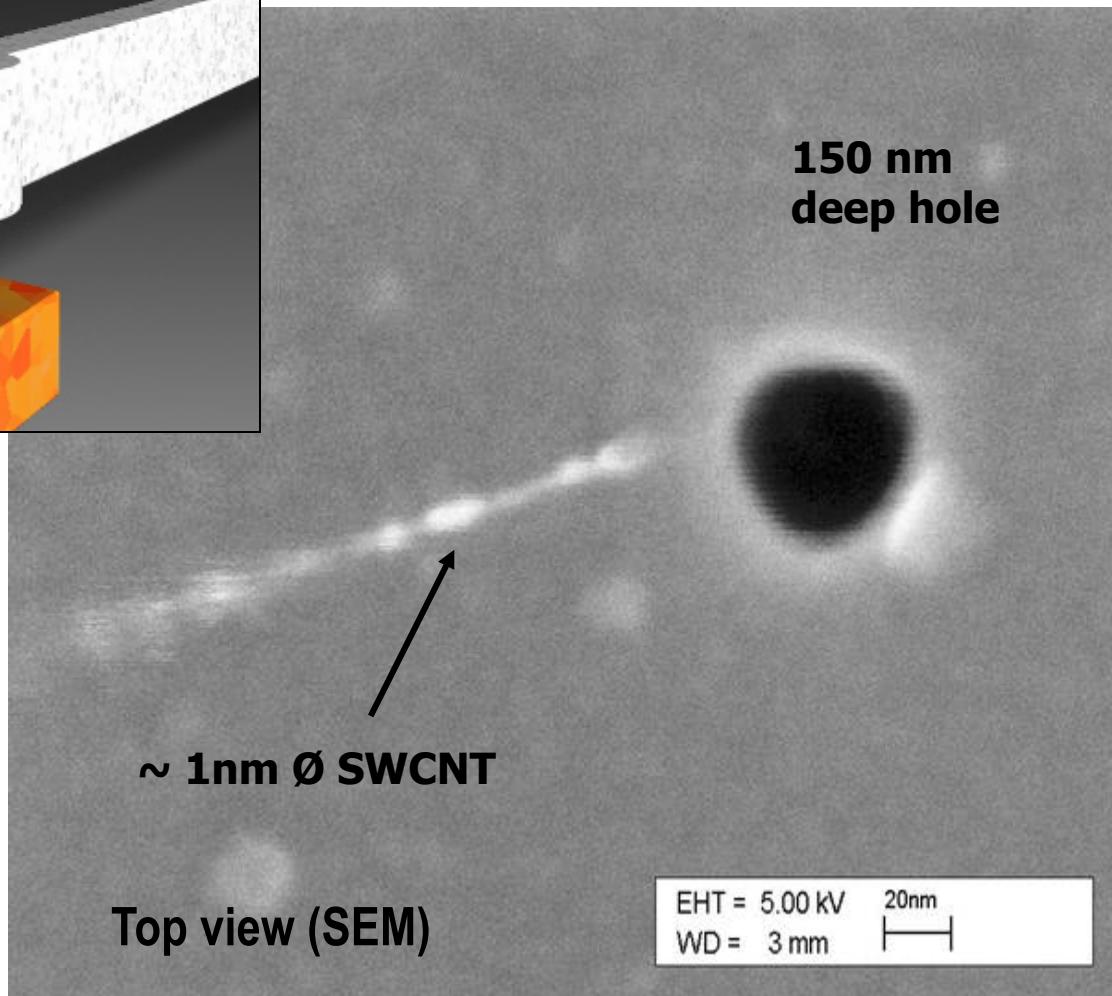
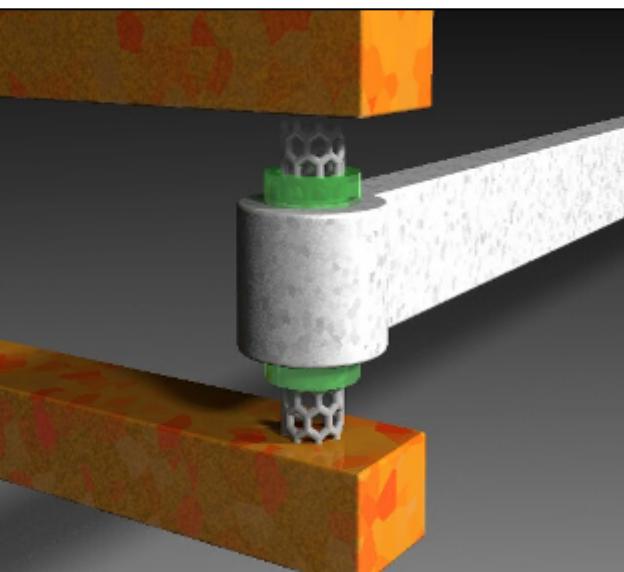


Accurate Positioning of CNTs ?



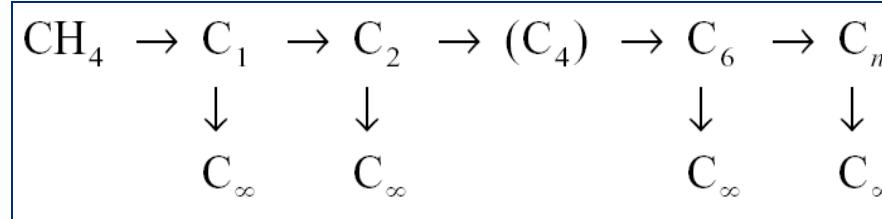
metal gate length can be adjusted to sub-nm accuracy by deposition

# The vertical transistor concept

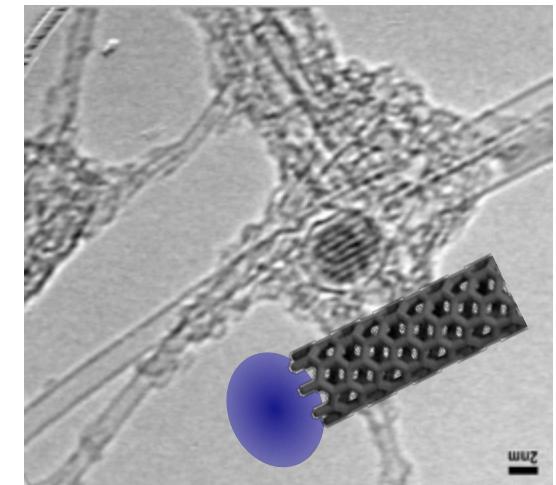
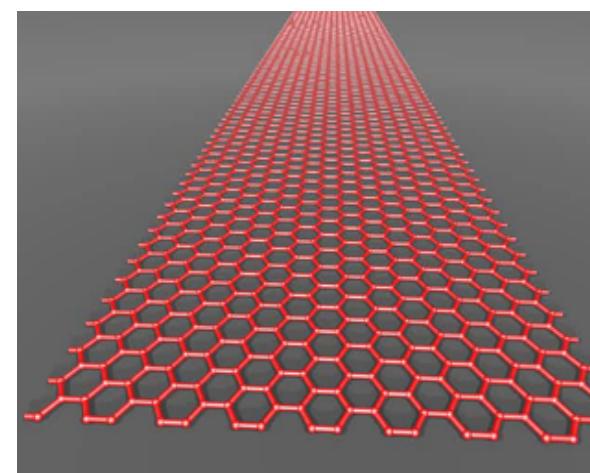
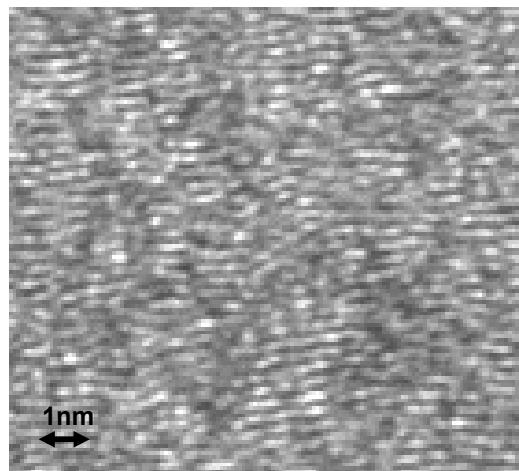




# CVD of nano-carbon structures



Pyrolysis of hydrocarbons

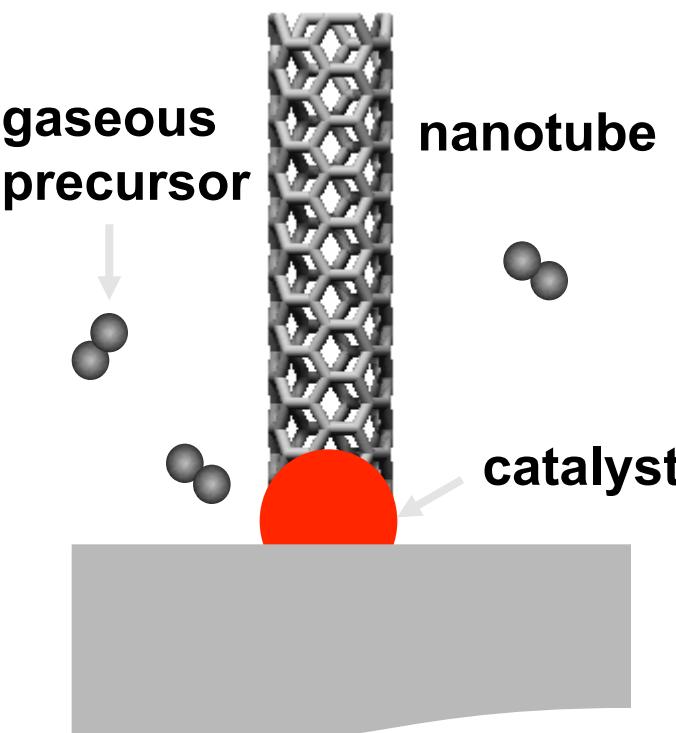


CNTs by CVD

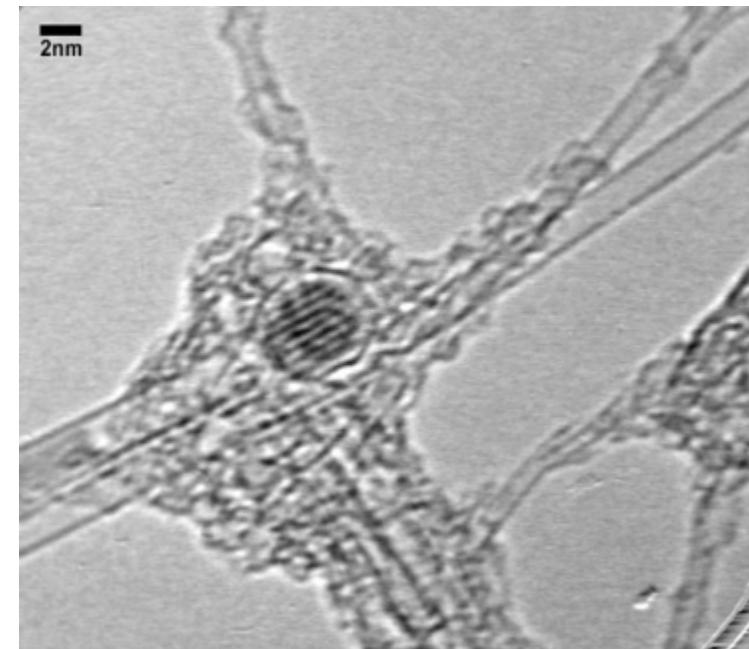
Pyrolytic Carbon  
(PyC)

Graphene by CVD

## Bottom-up (nanotubes, nanowires)



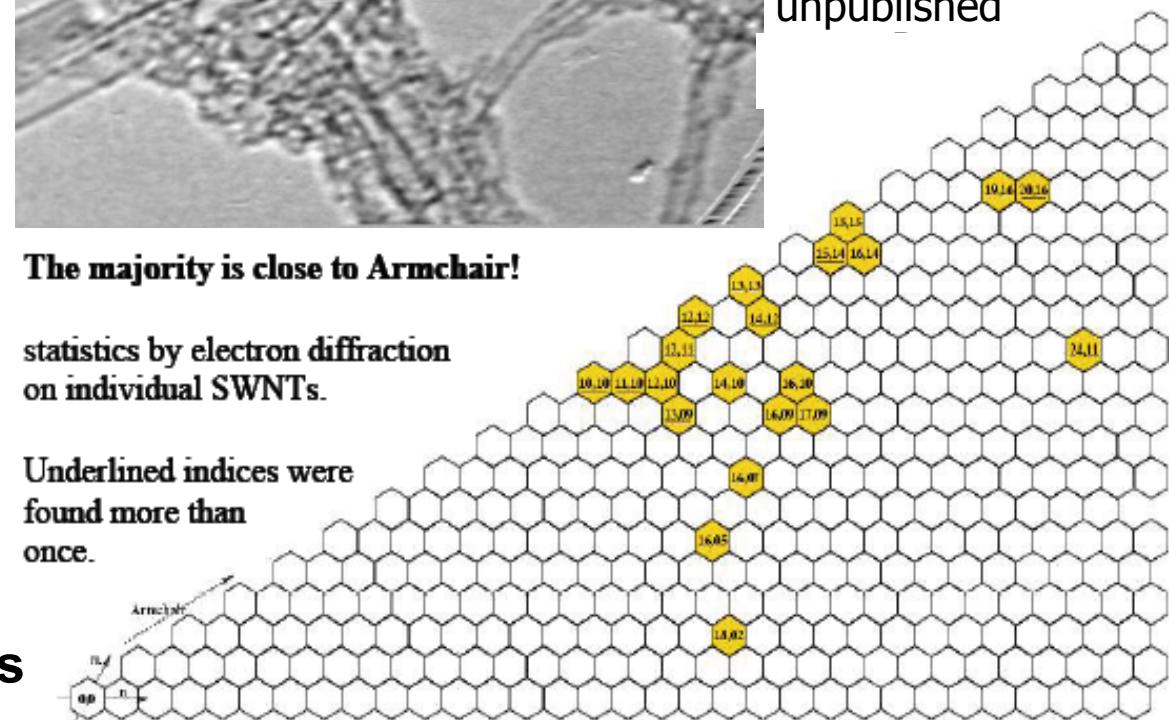
**self-organized 1-D structures**  
**high perfection**



**The majority is close to Armchair!**

statistics by electron diffraction  
on individual SWNTs.

**Underlined indices were  
found more than  
once.**

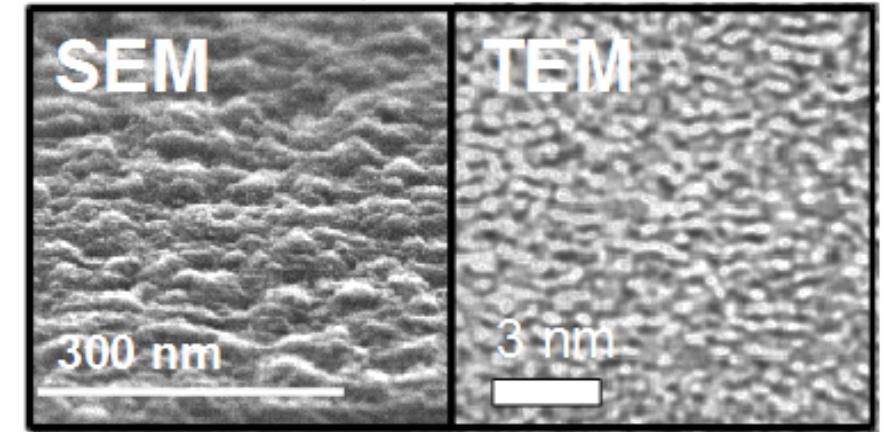
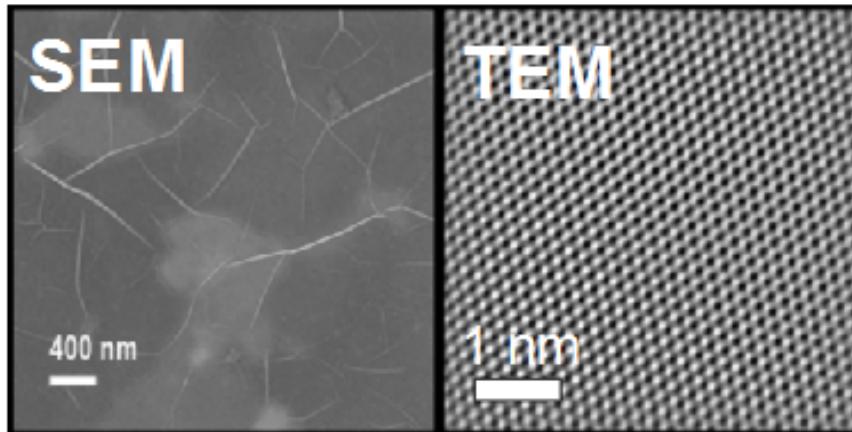
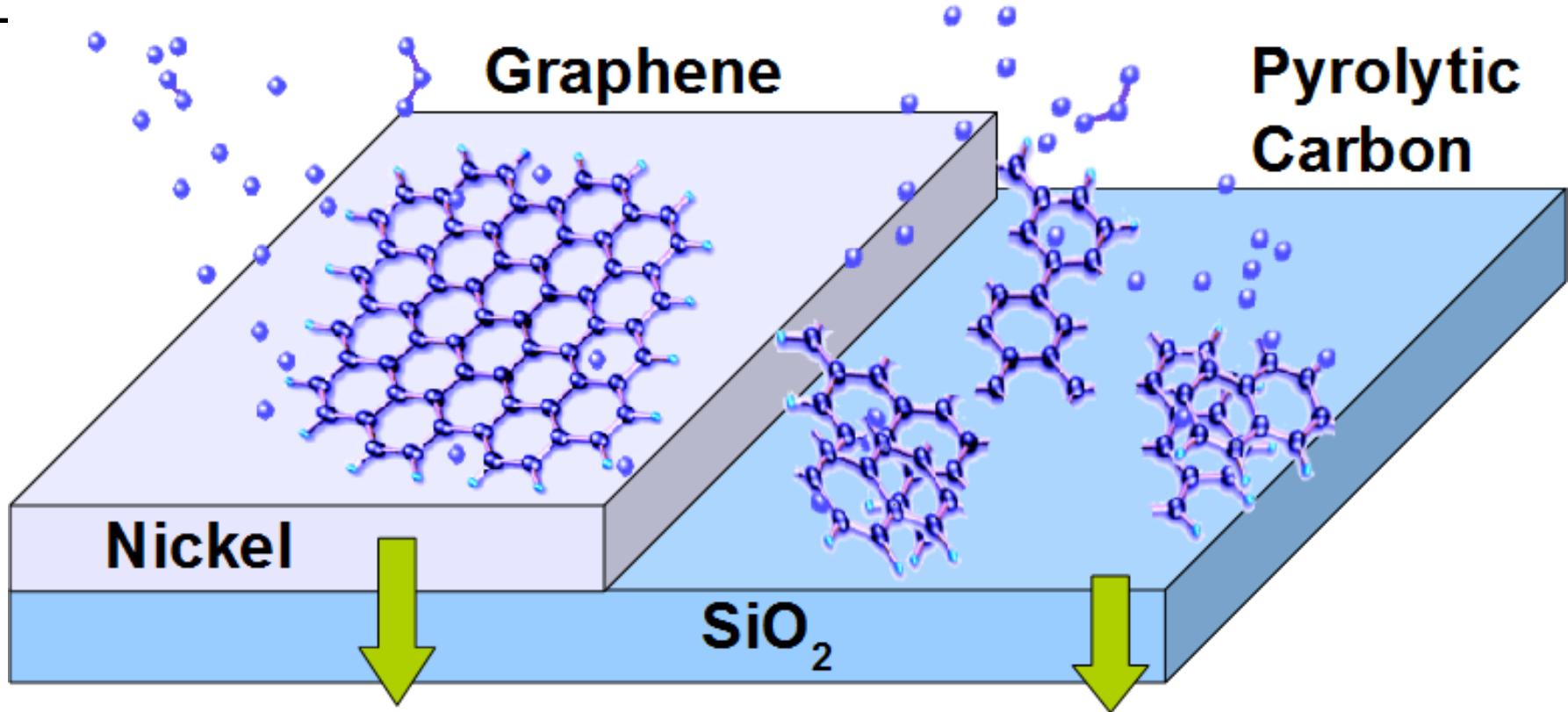


Lattice fringes  
match with walls  
of SWCNT a  
MoCo-Catalyst

J. C. Meyer, G.S  
Duesberg et al.,  
unpublished

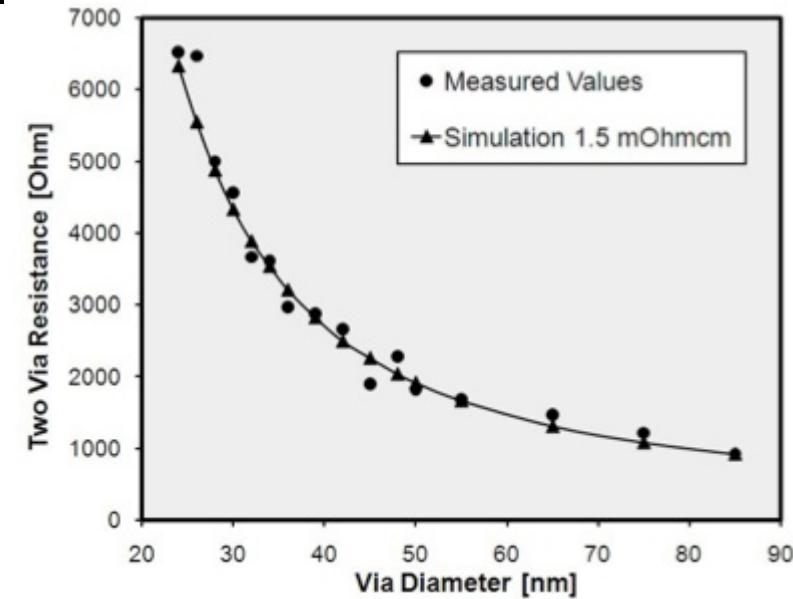
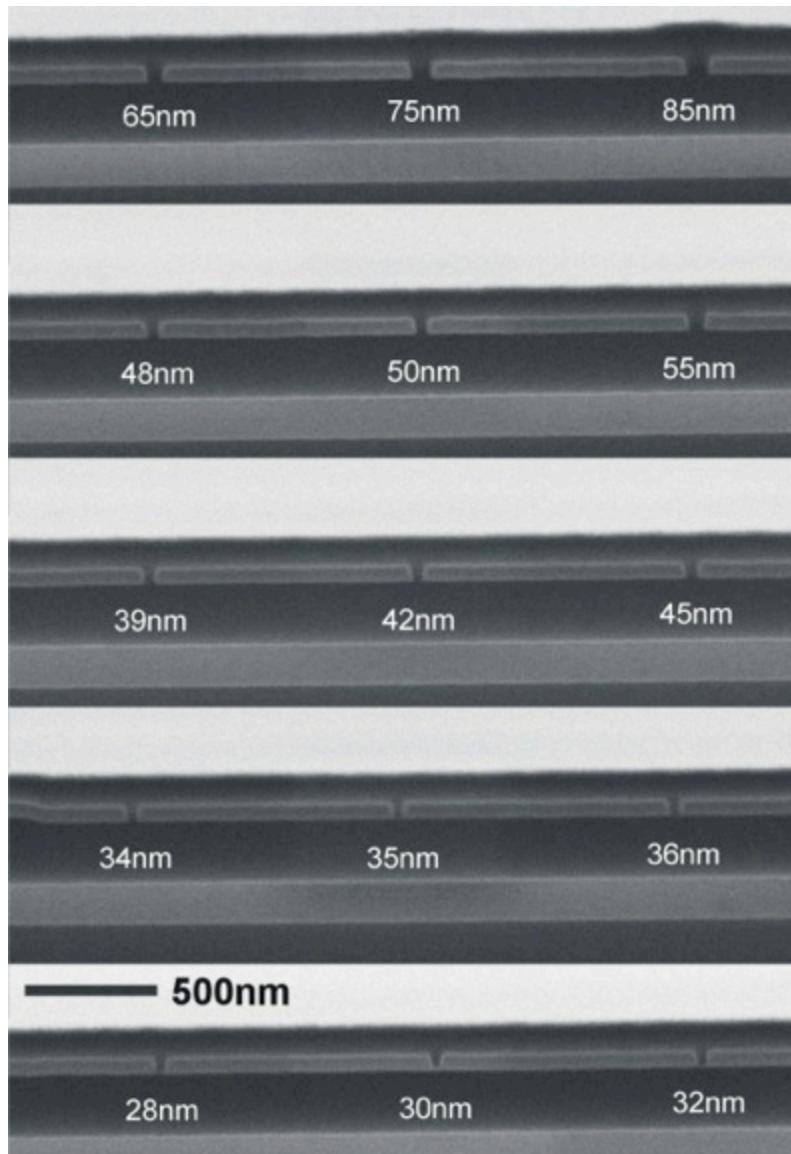


# Hetero-epitaxial CVD



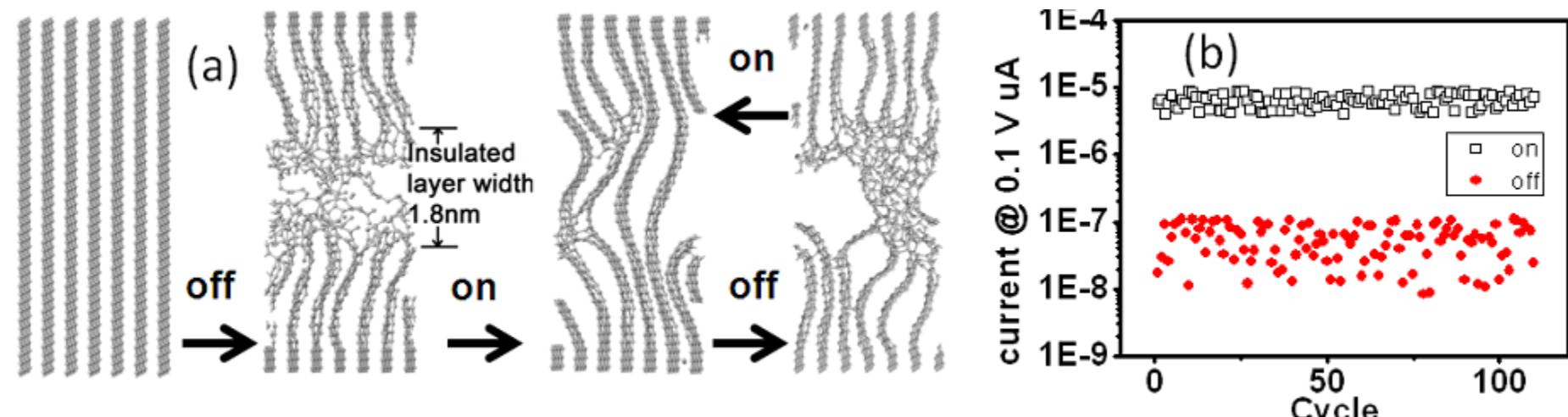


# Carbon Interconnects – PyC and CNTs

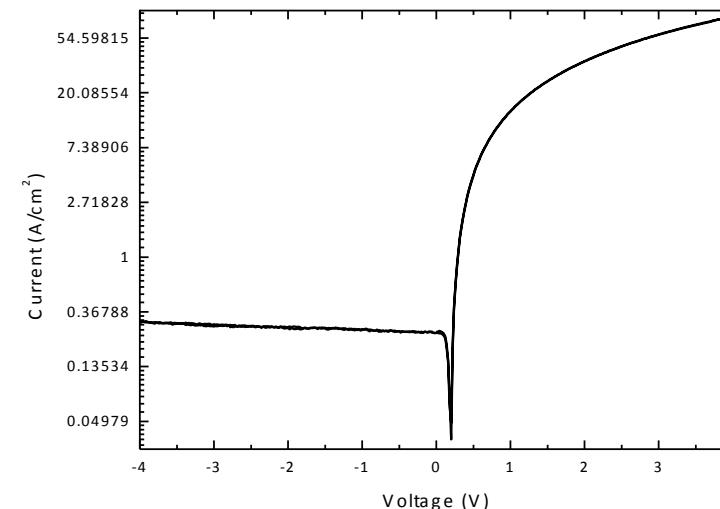
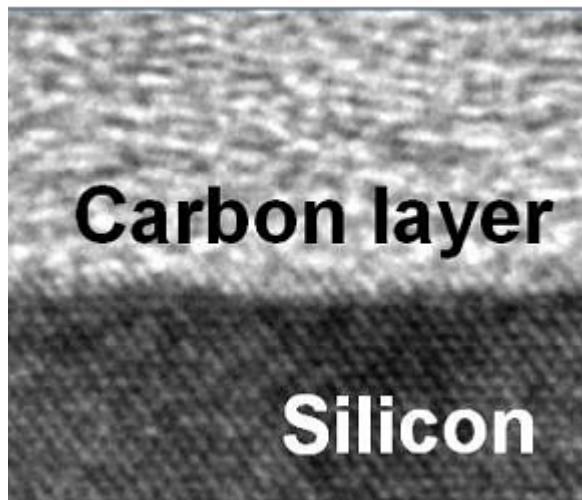




# Carbon devices: Memory and diode



Carbon CB Ram: Krepl et al. [arXiv:1012.4854v1](https://arxiv.org/abs/1012.4854v1), IDEM 2010



Schottky diode: Duesberg, Krepl, Graham et al.



# Outline

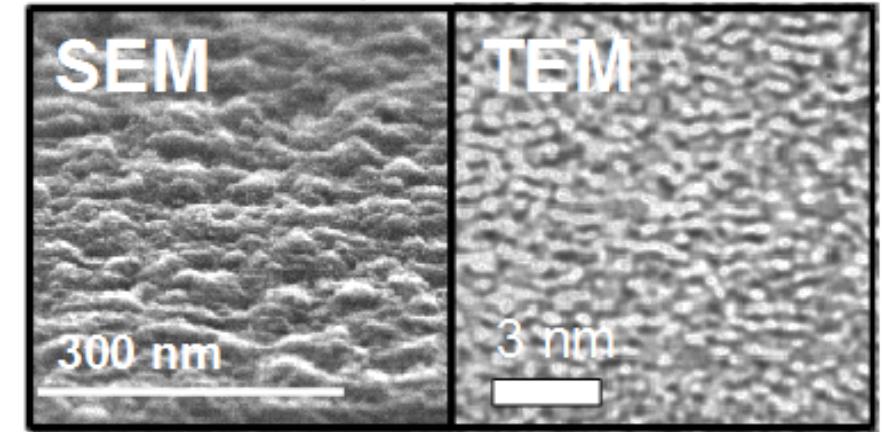
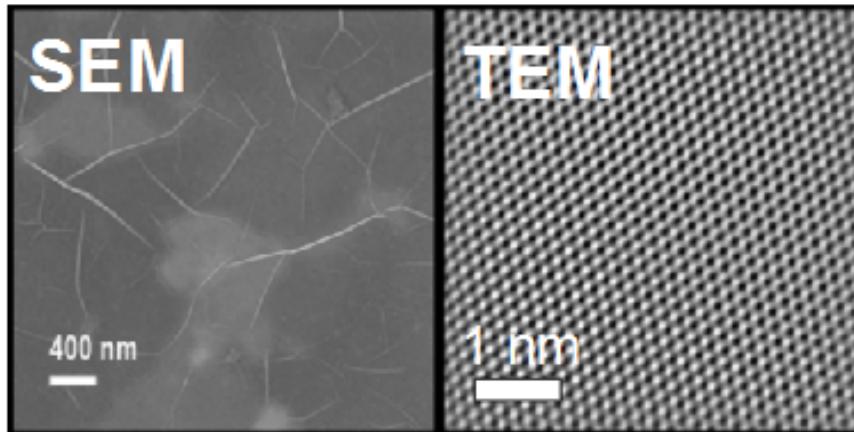
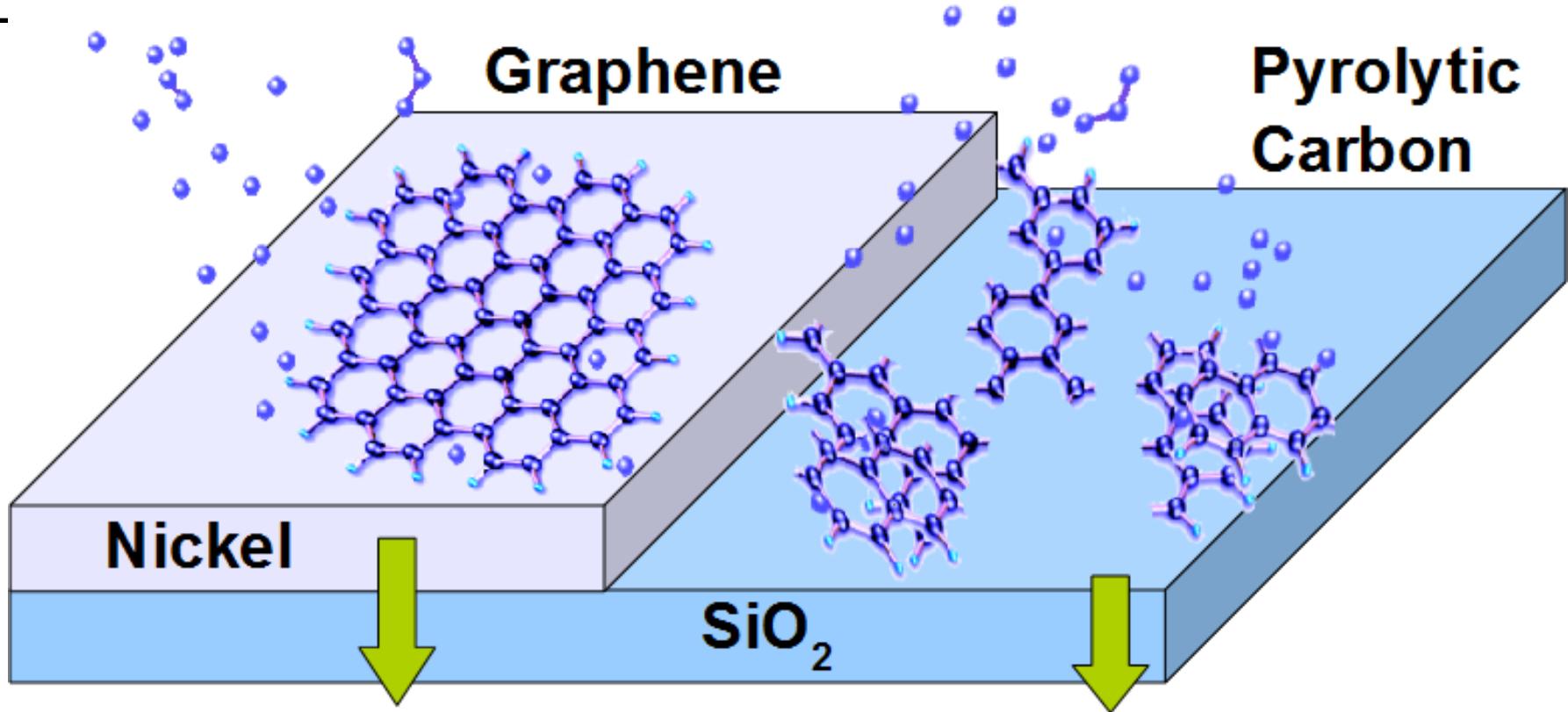
---



- ▶ Carbon Nano-structures: Applications in microelectronics
- ▶ Vertical Carbon devices
- ▶ Graphene Processing
- ▶ Other 2D Materials
- ▶ Carbon NEMS?
- ▶ Conclusions

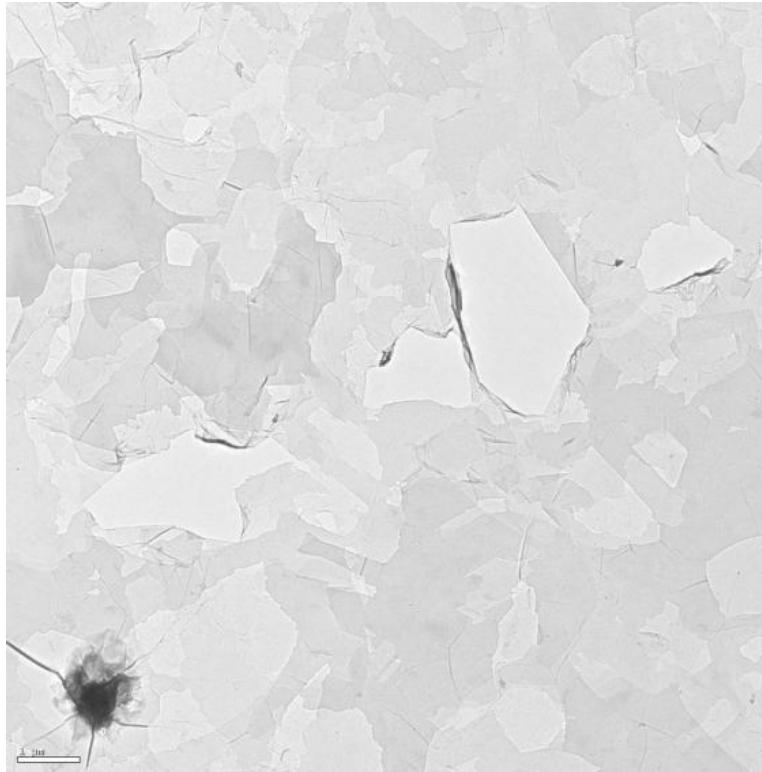


# Hetero-epitaxial CVD



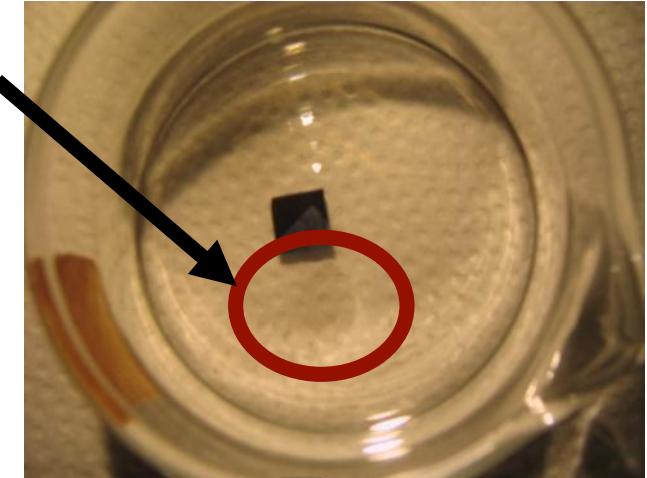


# CVD graphene & transfer



SEM

Graphene

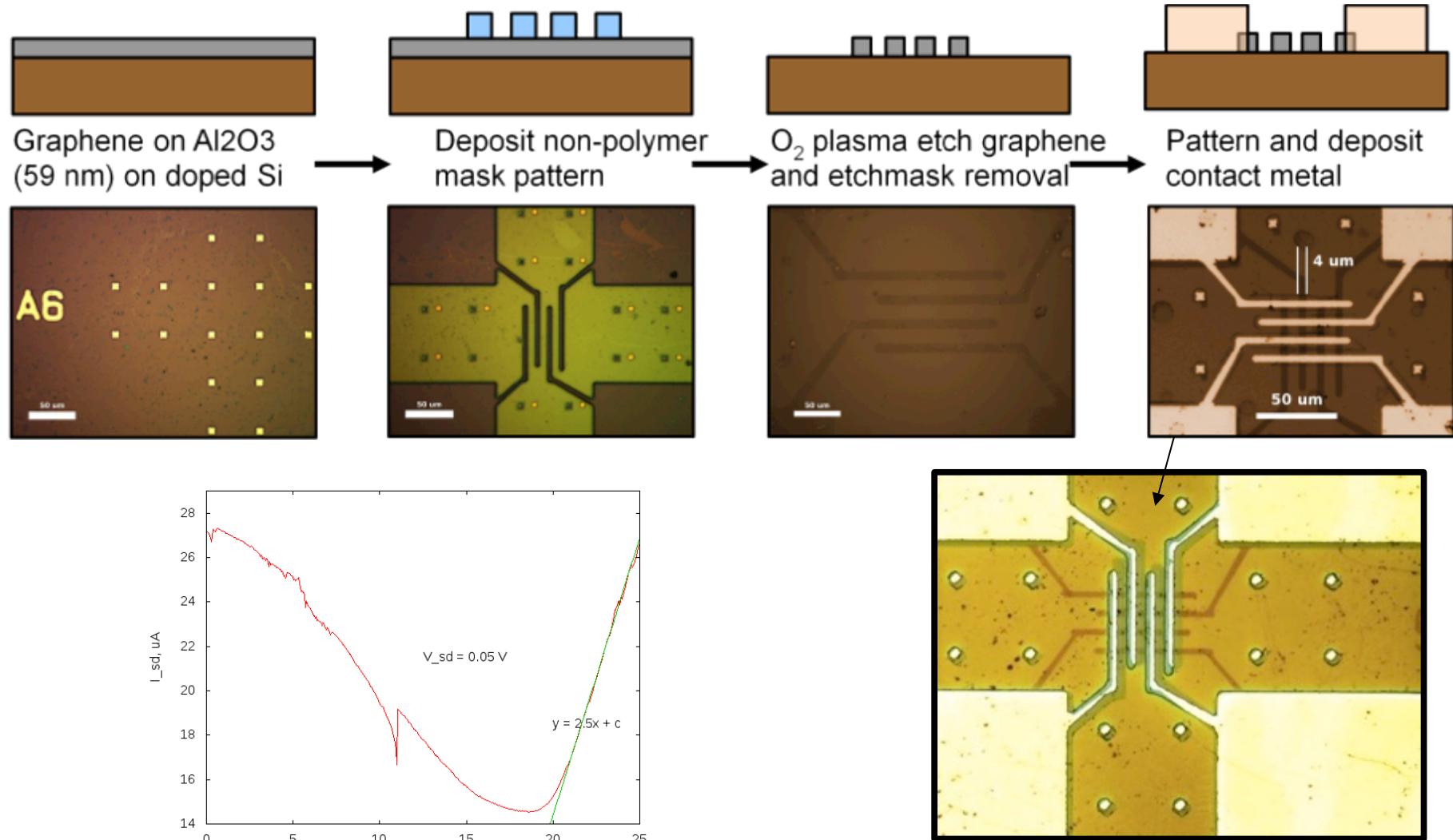


- Optical images of graphene films transferred to glass slides

S. Kumar et al. Chem Comm 2010

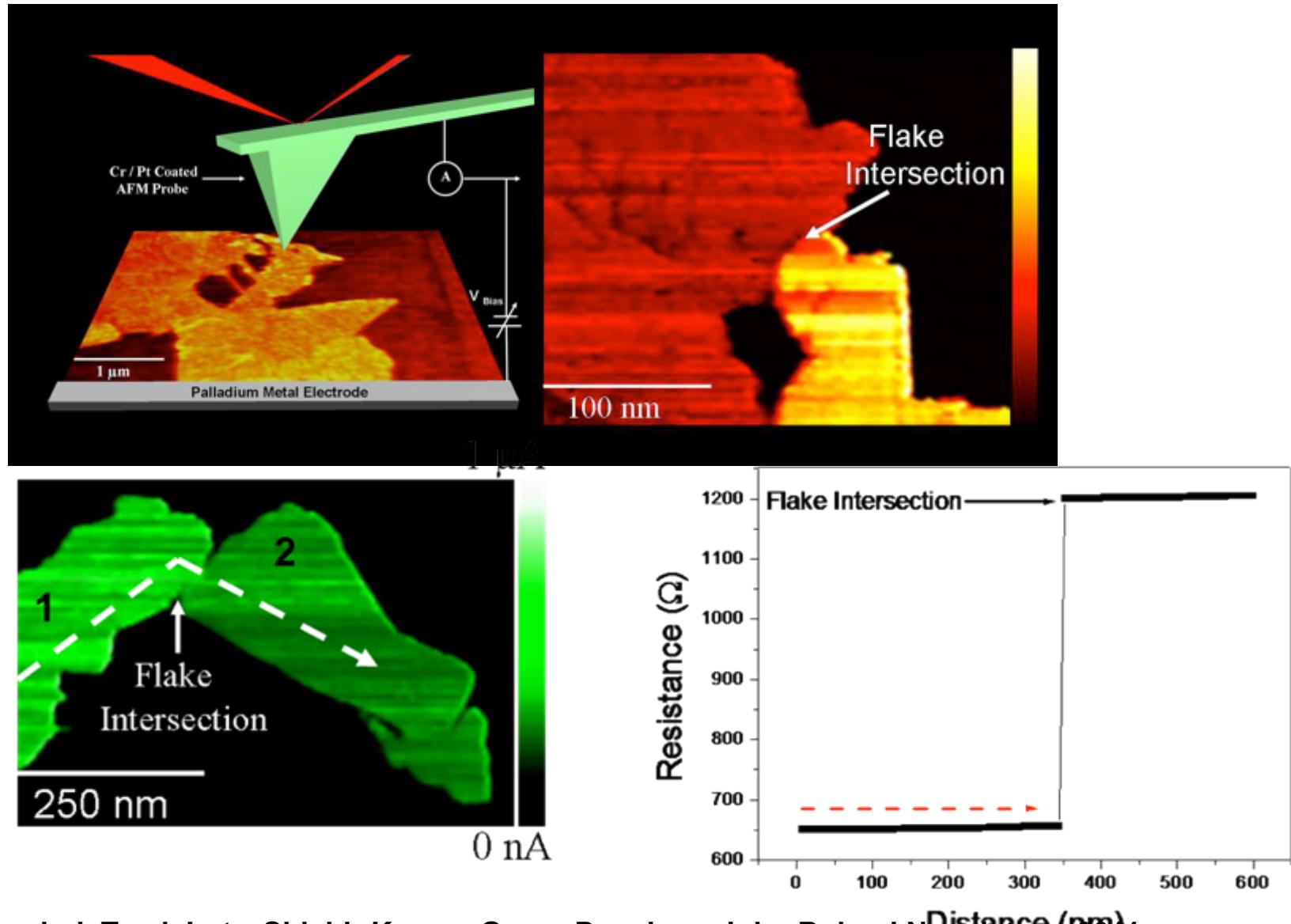


# Structuring graphene devices



Kumar, S.; Peltekis, N.; Lee, K.; Kim, H. Y.; Duesberg, G. S.  
*Nanoscale Research Letters*, 2011, 6, 390

# Conductive AFM in graphene films

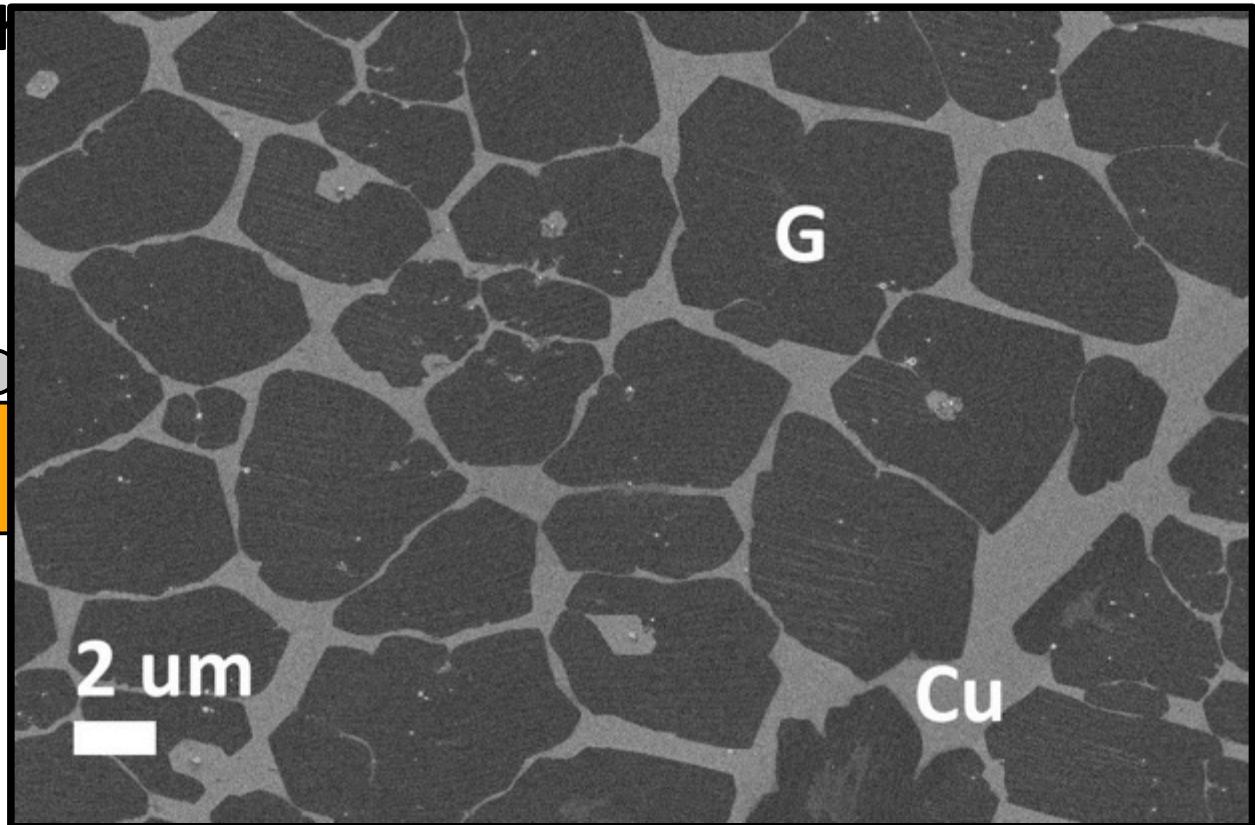
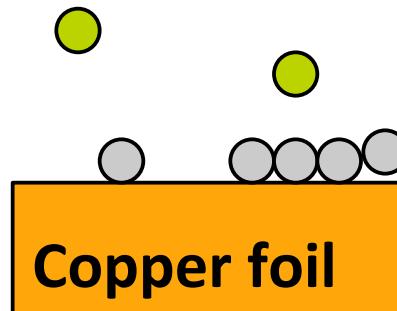


# Graphene on Copper

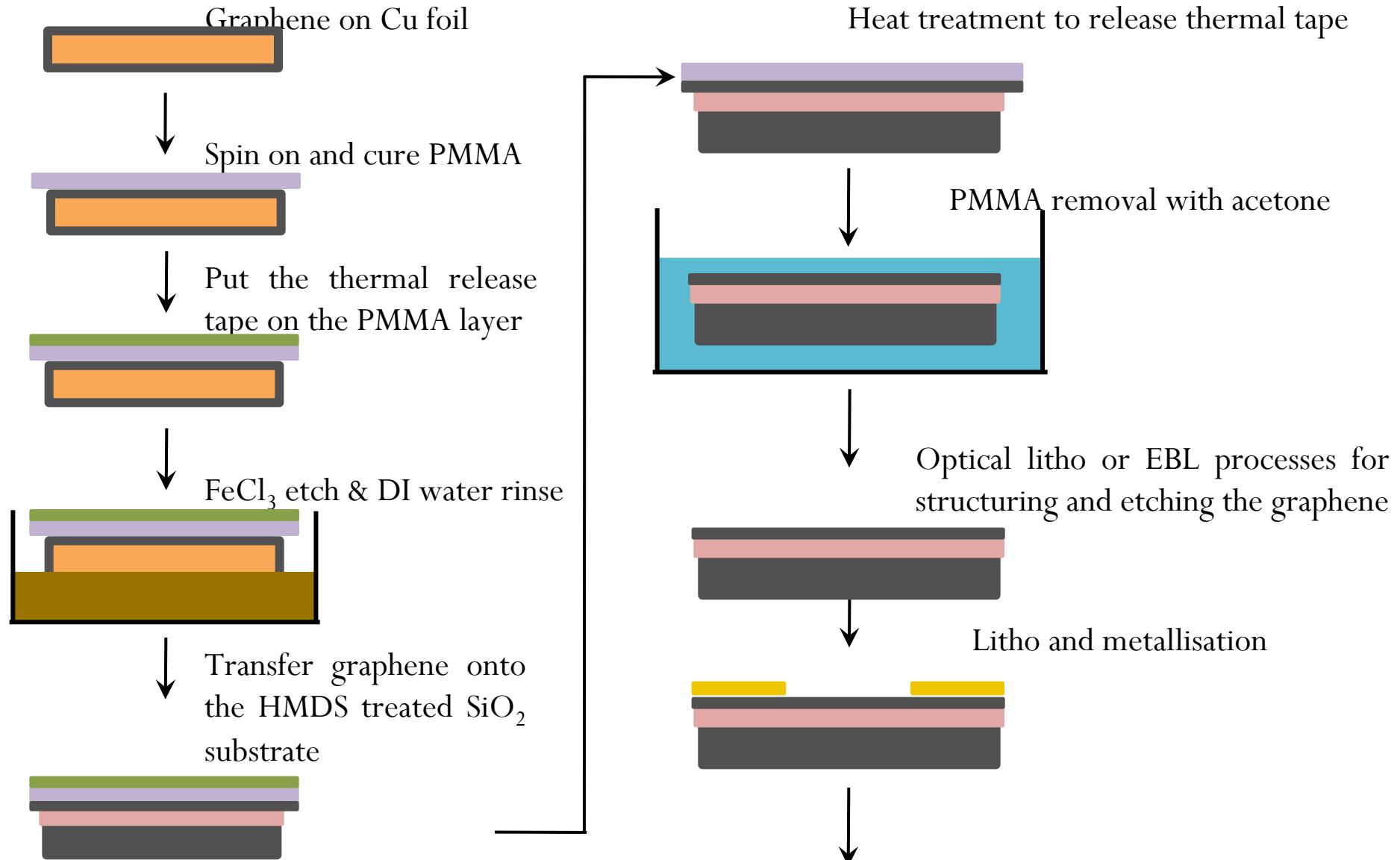
Low solubility of carbon

Less catalytic th

Lattice match

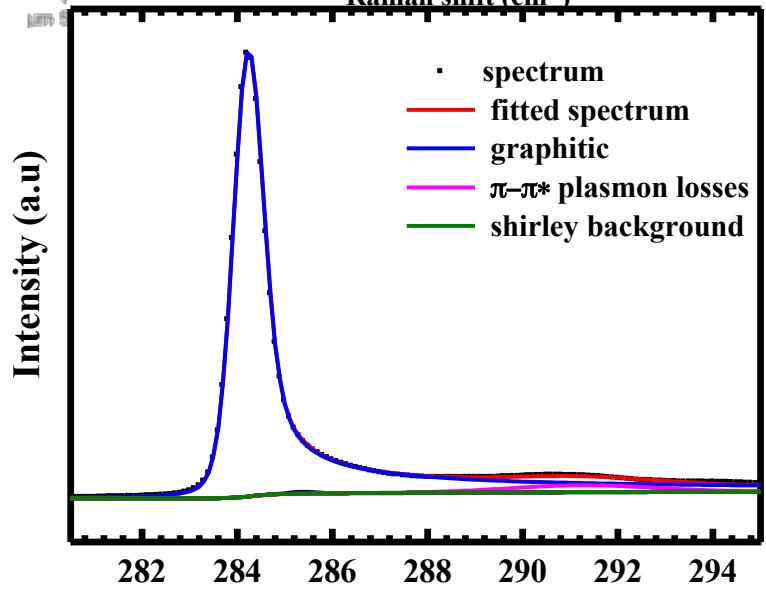
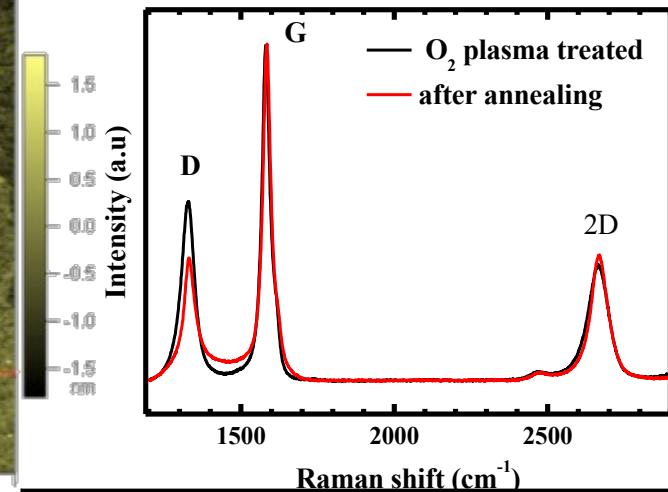
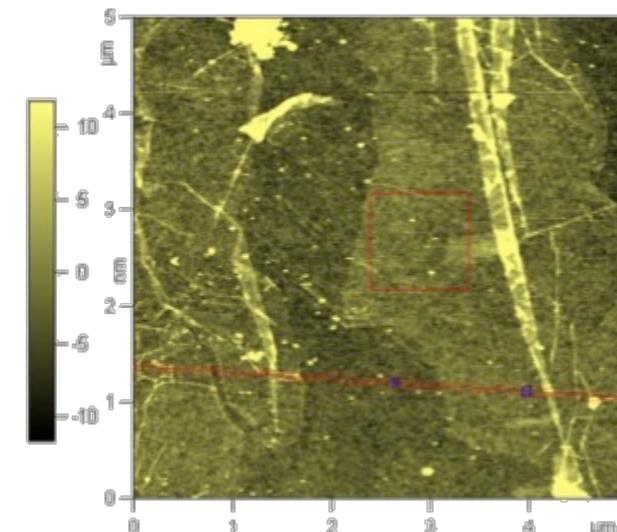
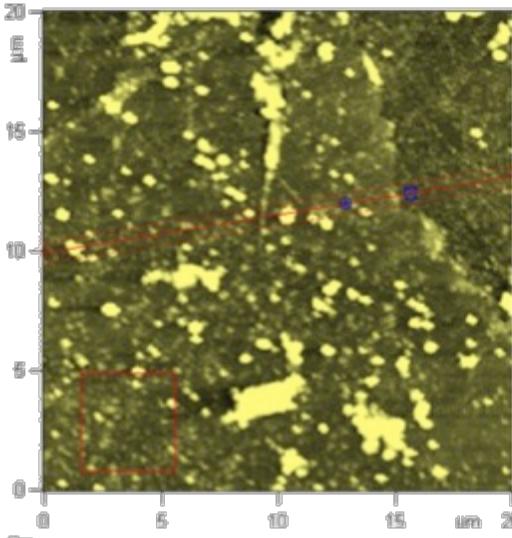


# Polymer transfer technique for graphene♪



# Analysis of plasma cleaned graphene

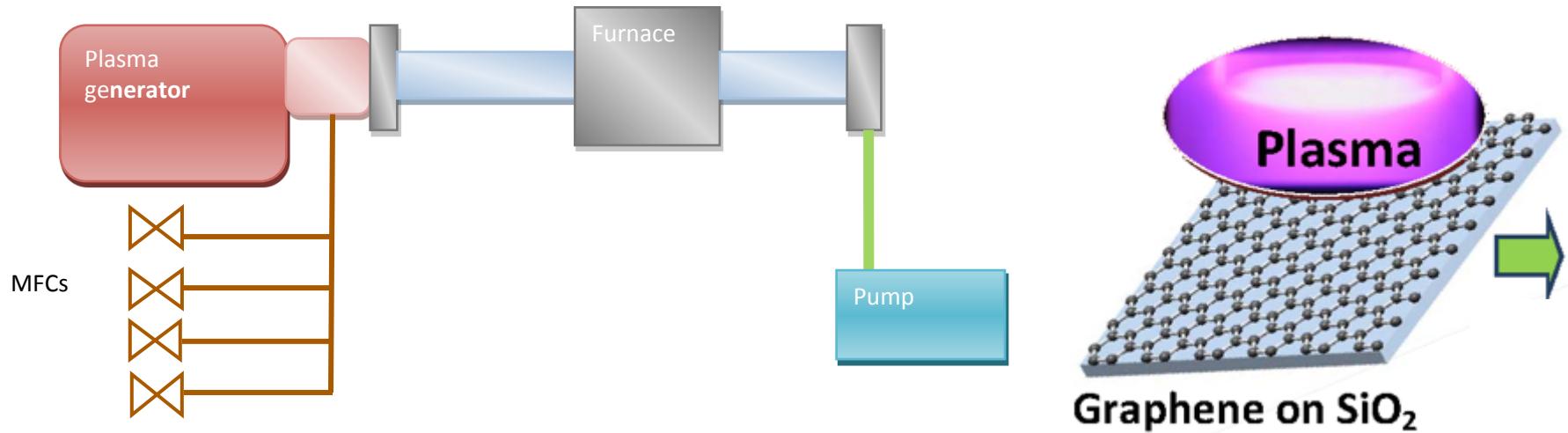
Graphene transferred with polymers is cleaned with remote plasma at low temps



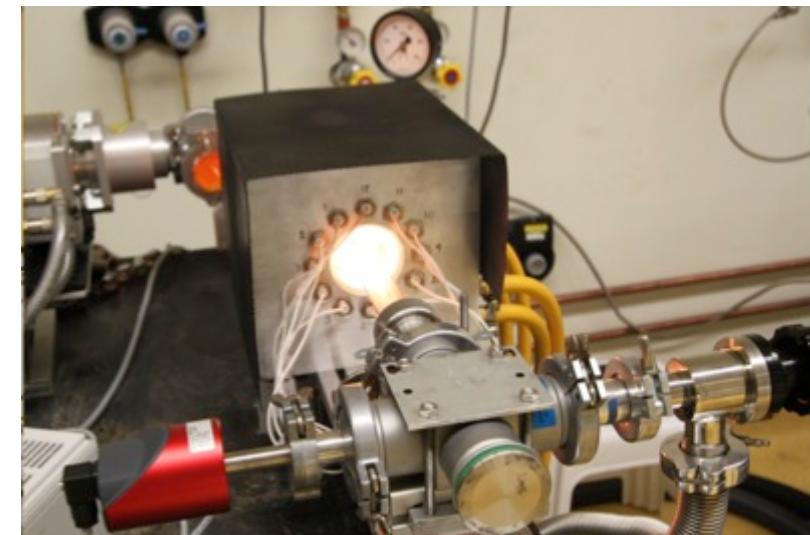
Peltekis, Duesberg et al. Carbon, accepted



# Cleaning of graphene with plasmas

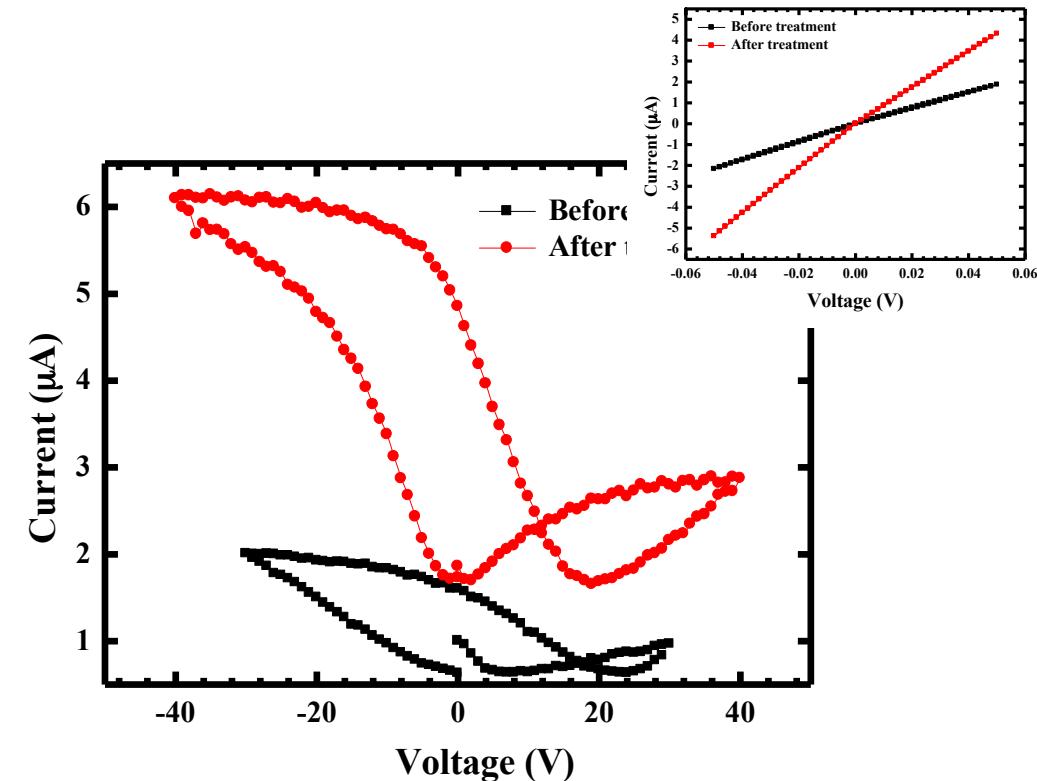
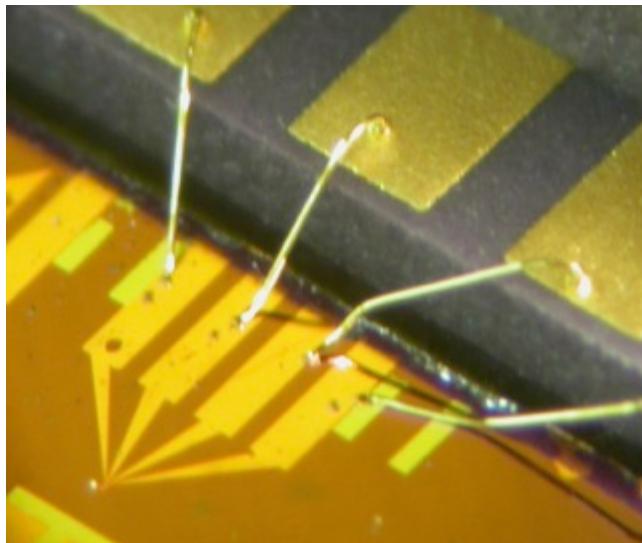
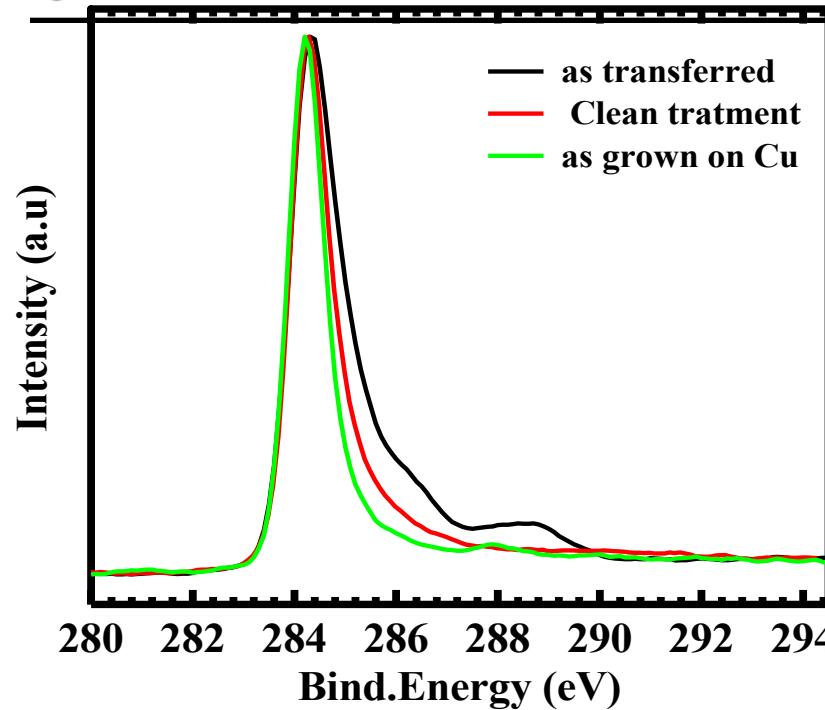


"Chemical" plasma by a remote source  
(R<sup>3</sup>T TWR 2000-GEN, 400V) 1000W .  
pressure of 1 torr flow rates of 100 sccm  
Oxygen and Hydrogen





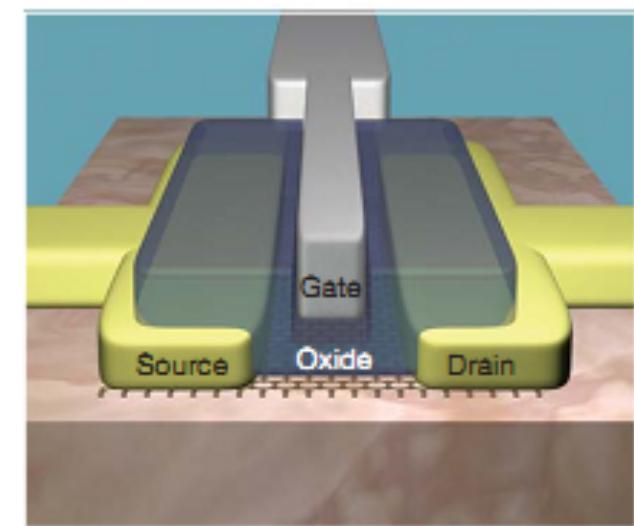
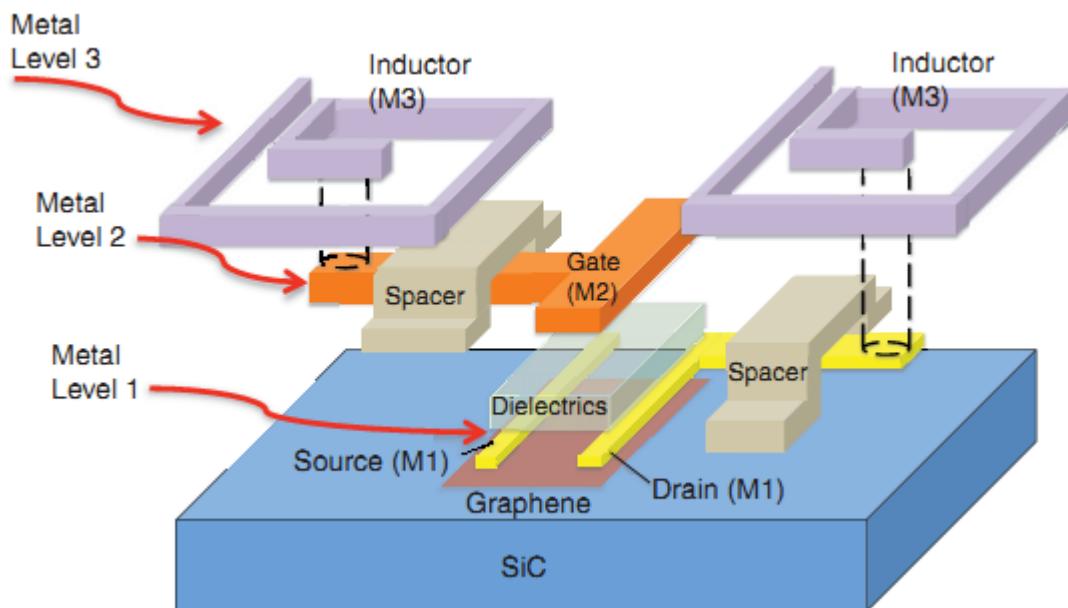
# Cleaning of graphene with plasmas only



In-situ cleaning possible!  
Conductivity and mobilities increased  $\sim 200 \text{ cm}^2/\text{Vs}$  after plasma treatment  
This applies to all graphene type samples

Peltekis, Duesberg et al. Carbon, accepted

Band gap ?

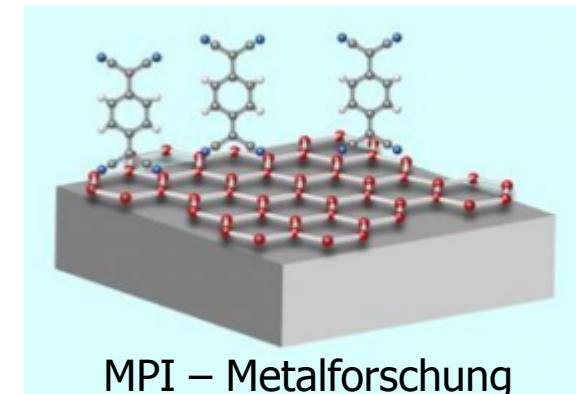
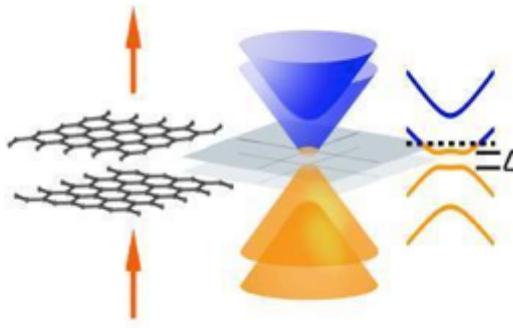


Avouris group IBM

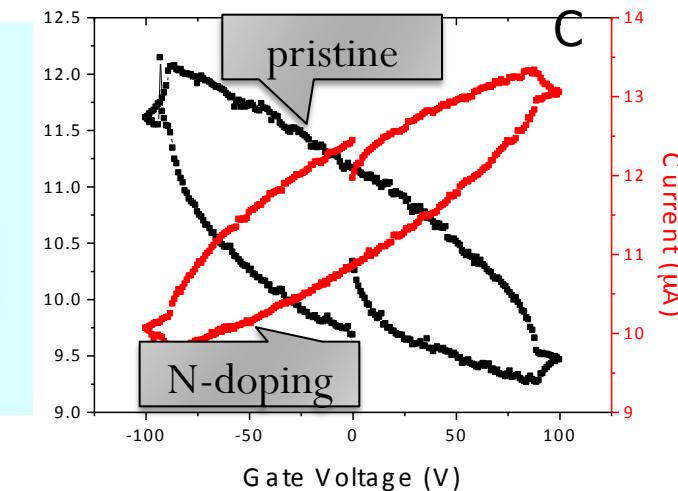
# Band gap engineering in graphene

## Double layers

Zhang et al. 2009 Nature

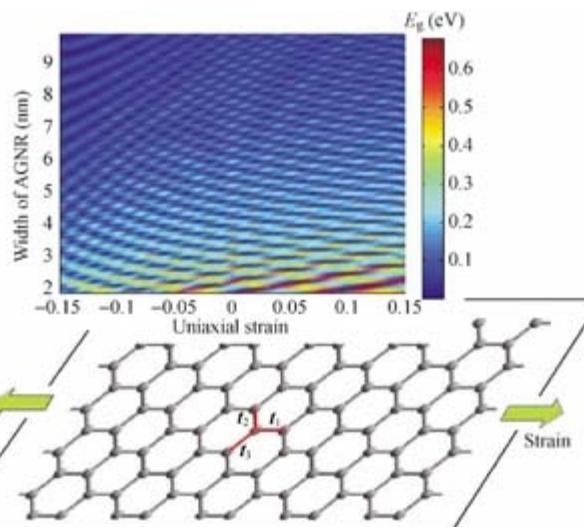


## Functionalisation/ Doping



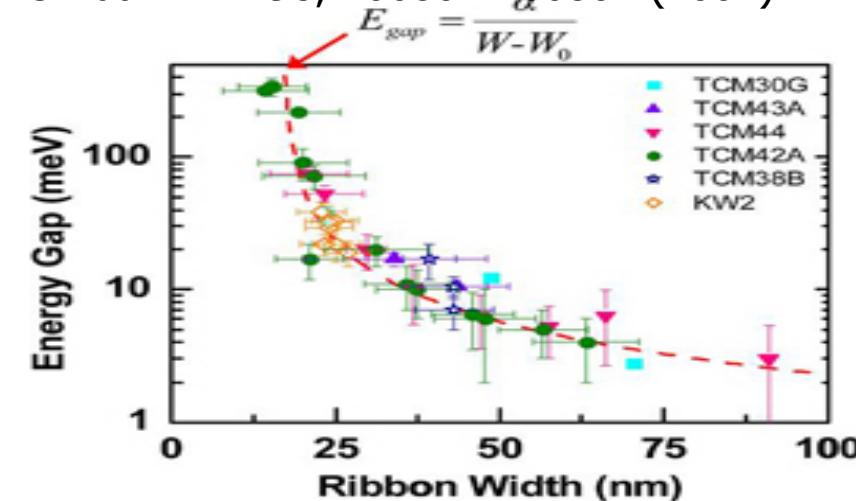
## Stress

Lu, Nano Research 2009



## Cut out/size effect

Melinda Y. PRL98, 206801-206804 (2007).

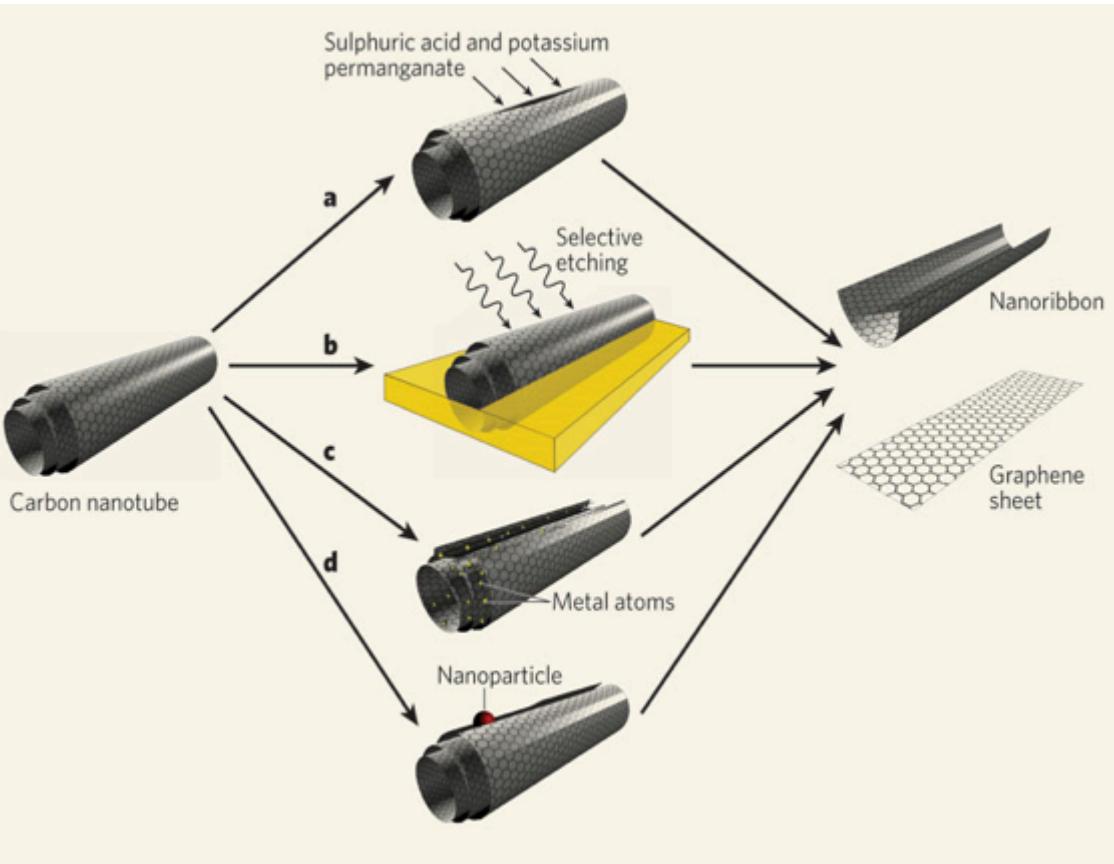


# Graphene ribbons – chemical routes

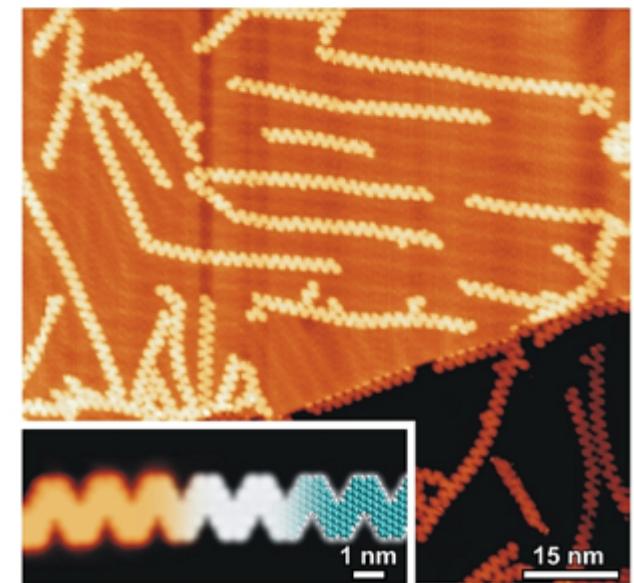
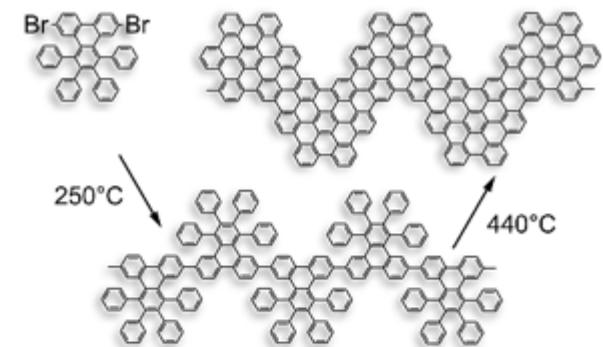
Materials science: Nanotubes unzipped

Mauricio Terrones

Nature 458, 845-846(16 April 2009)



Atomically defined structures!

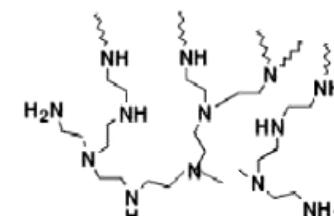
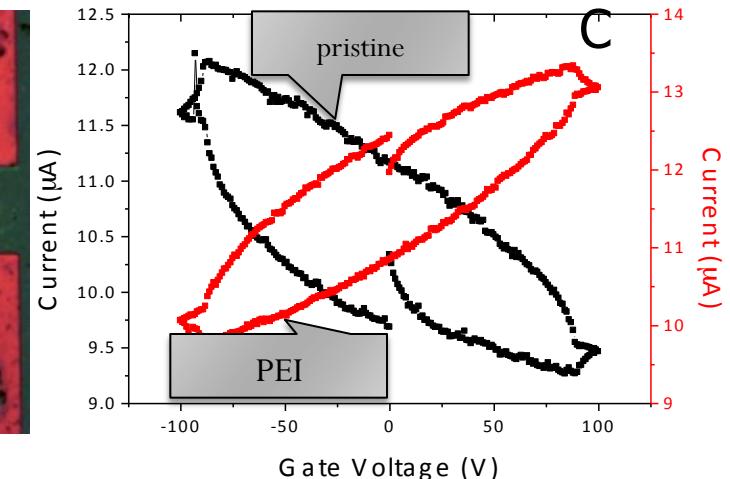
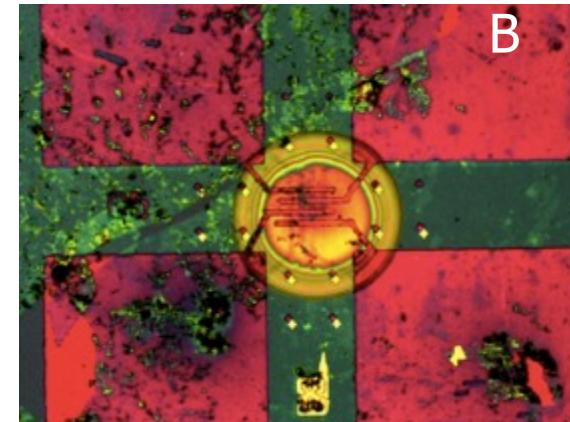


J. Cai, et al. Nature, 2010

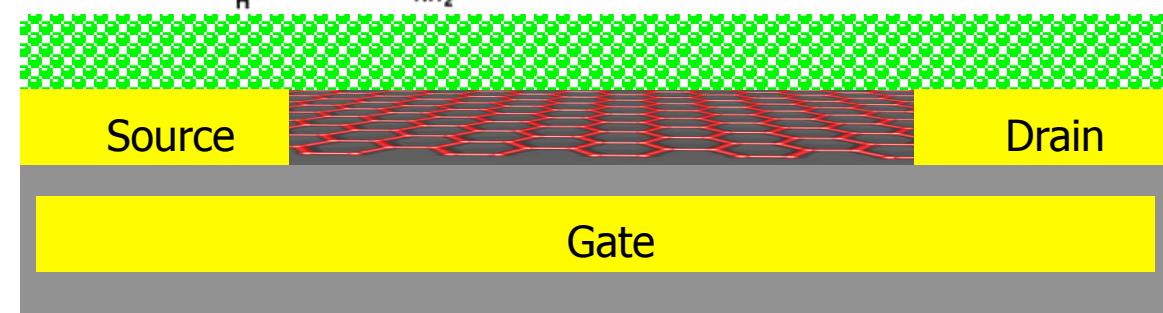
Same or even more problems as with nanotubes



# Top coated graphene Fets



n-Doping : Polyethylenimine (PEI)



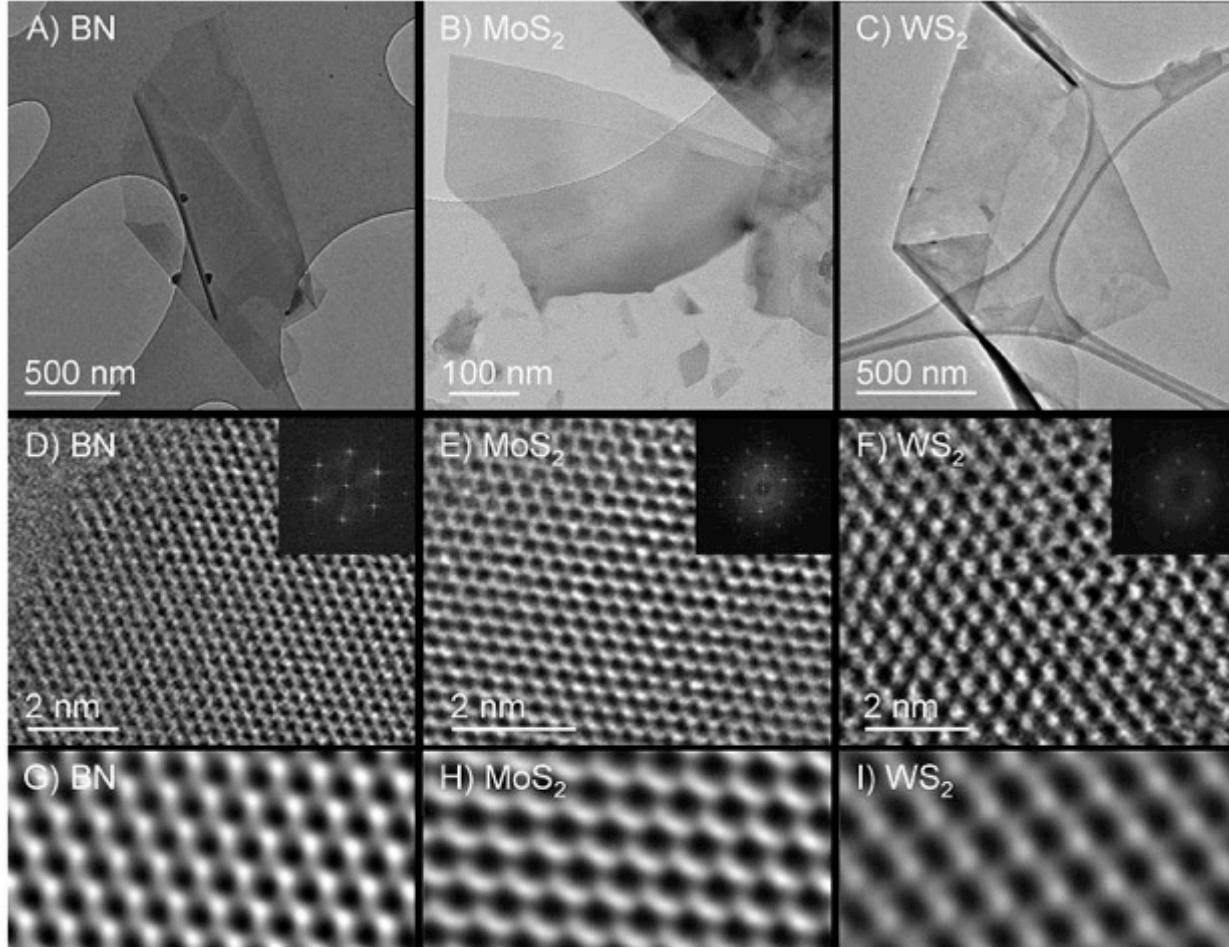


# Outline

---



- ▶ Carbon Nano-structures: Applications in microelectronics
- ▶ Vertical Carbon devices
- ▶ Graphene Processing
- ▶ Other 2D Materials
- ▶ Carbon NEMS?
- ▶ Conclusions

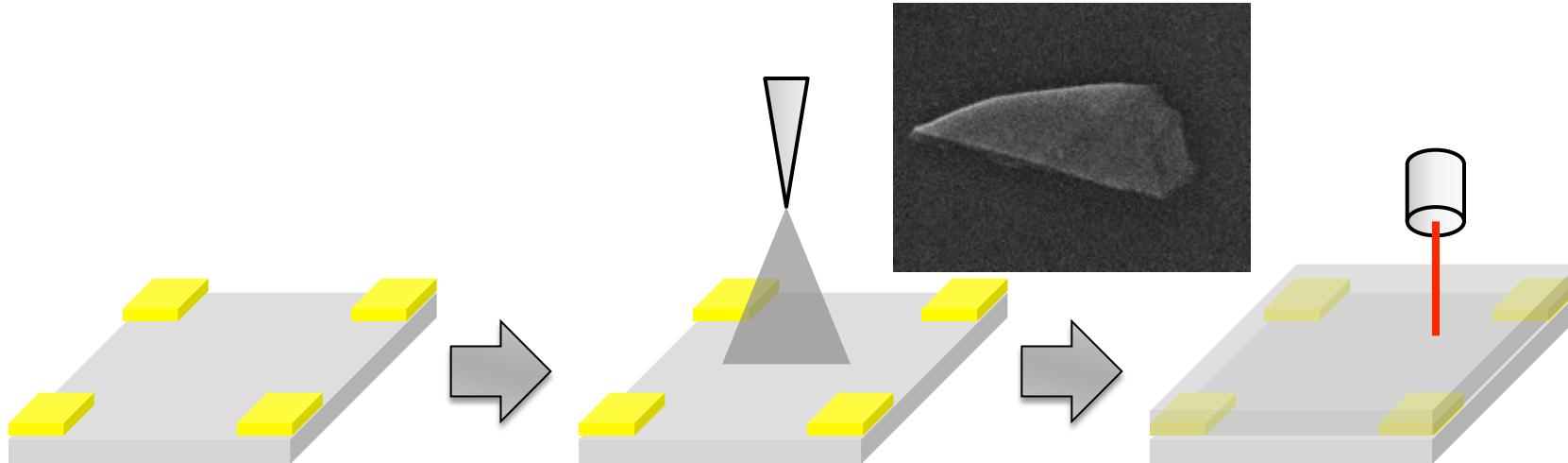


Layered compounds such as  $\text{MoS}_2$ ,  $\text{WS}_2$ ,  $\text{MoSe}_2$ ,  $\text{MoTe}_2$ ,  $\text{TaSe}_2$ ,  $\text{NbSe}_2$ ,  $\text{NiTe}_2$ ,  $\text{BN}$ , and  $\text{Bi}_2\text{Te}_3$  can be efficiently dispersed (also topological insulators?!)

Jonathan N. Coleman, Hye-Young Kim, Kangho Lee, Gyu Tae Kim, Georg S. Duesberg, Nicolosi, et al, "Two-Dimensional Nanosheets Produced by Liquid Exfoliation of Layered Materials", **Science**, 568-571, 2011



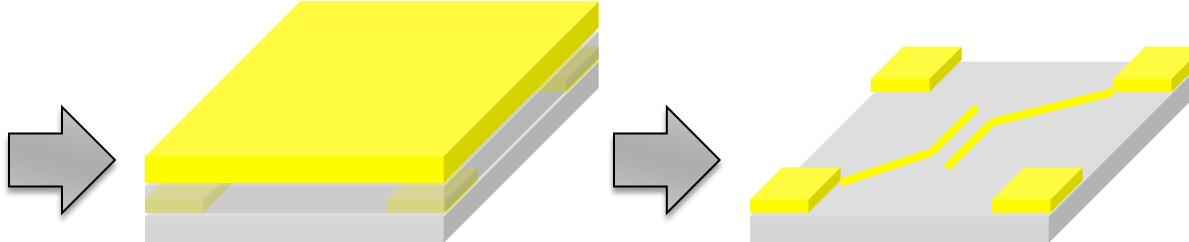
# Contacting individual MoS<sub>2</sub> flakes



Si/SiO<sub>2</sub> Substrate♪

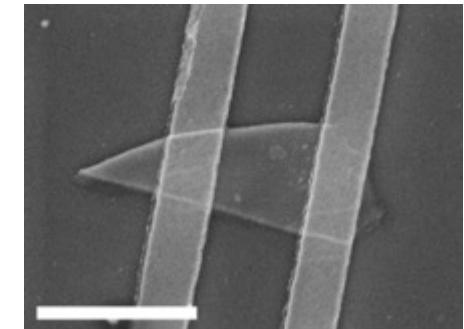
MoS<sub>2</sub> Spraying♪

Contact  
Patterning♪

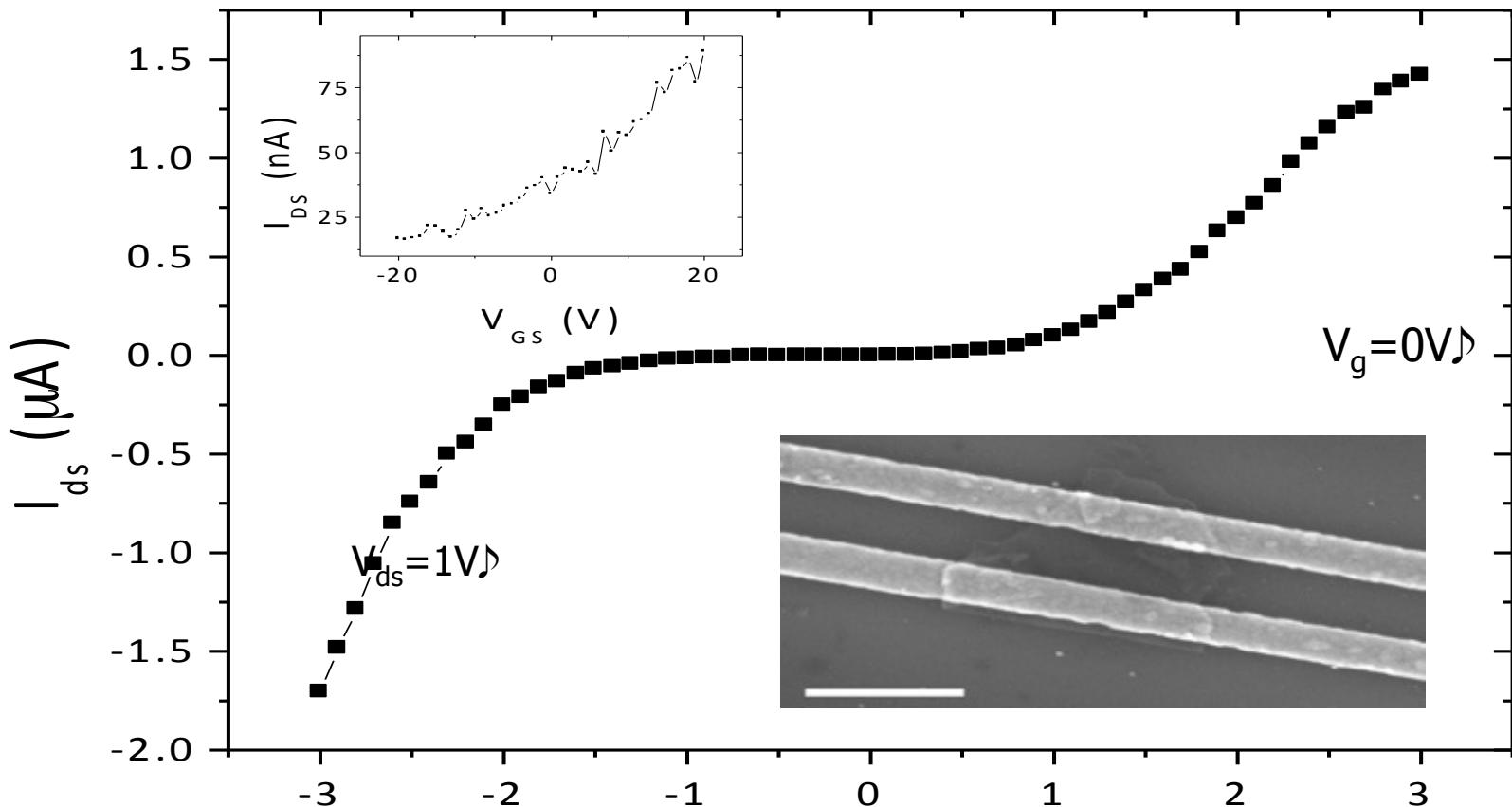


Metal Deposition♪

Lift-off♪

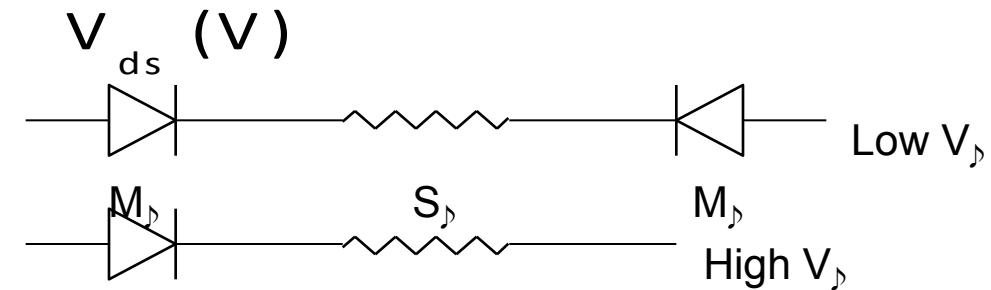


# E-beam contacted MoS<sub>2</sub> flake



Up to  $\mu = 195 \text{ cm}^2/\text{Vs}$  can be extracted based on a model taken into thermal field emission (MSM). (similar to B. Radisavljevic , A. Kis, Nature Nano 2011)

**Lee, Kim, Duesberg et al. Adv Mater., 2011**





# Outline

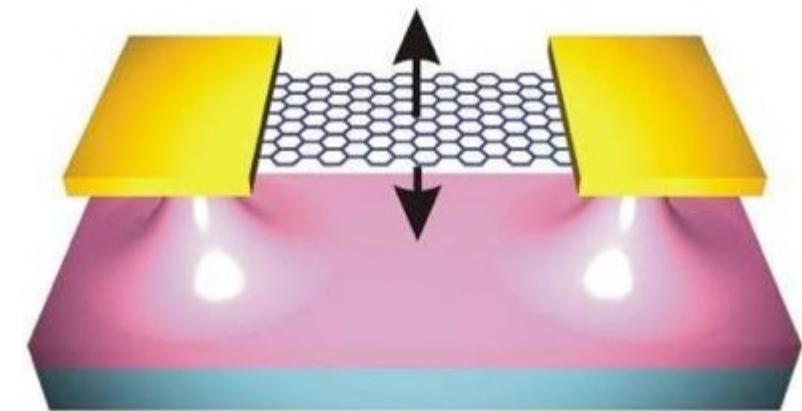
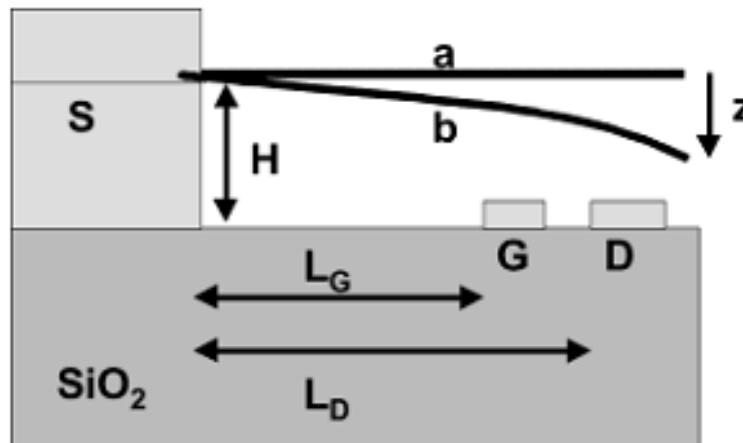
---



- ▶ Carbon Nano-structures: Applications in microelectronics
- ▶ Vertical Carbon devices
- ▶ Graphene Processing
- ▶ Other 2D Materials
- ▶ Carbon NEMS?
- ▶ Conclusions

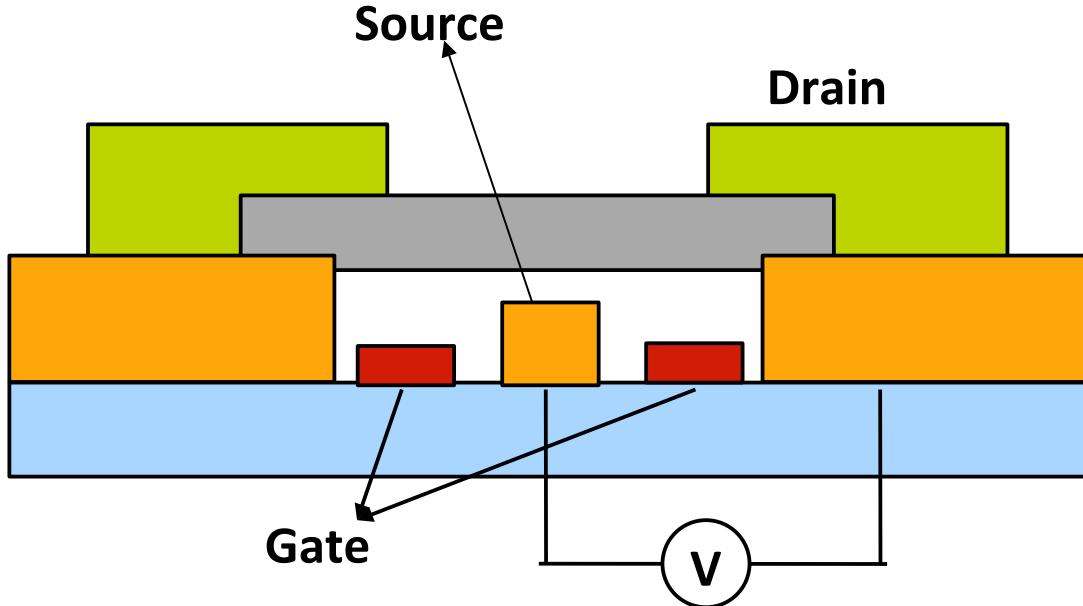
# CNT relay and graphene resonator

- High on/off ratio
- Low power
- High speed
- Carbon stable and light = high Q factors



Bachthold et al. 2009

Nanorelay, Lee et al.  
Nanoletters 2003

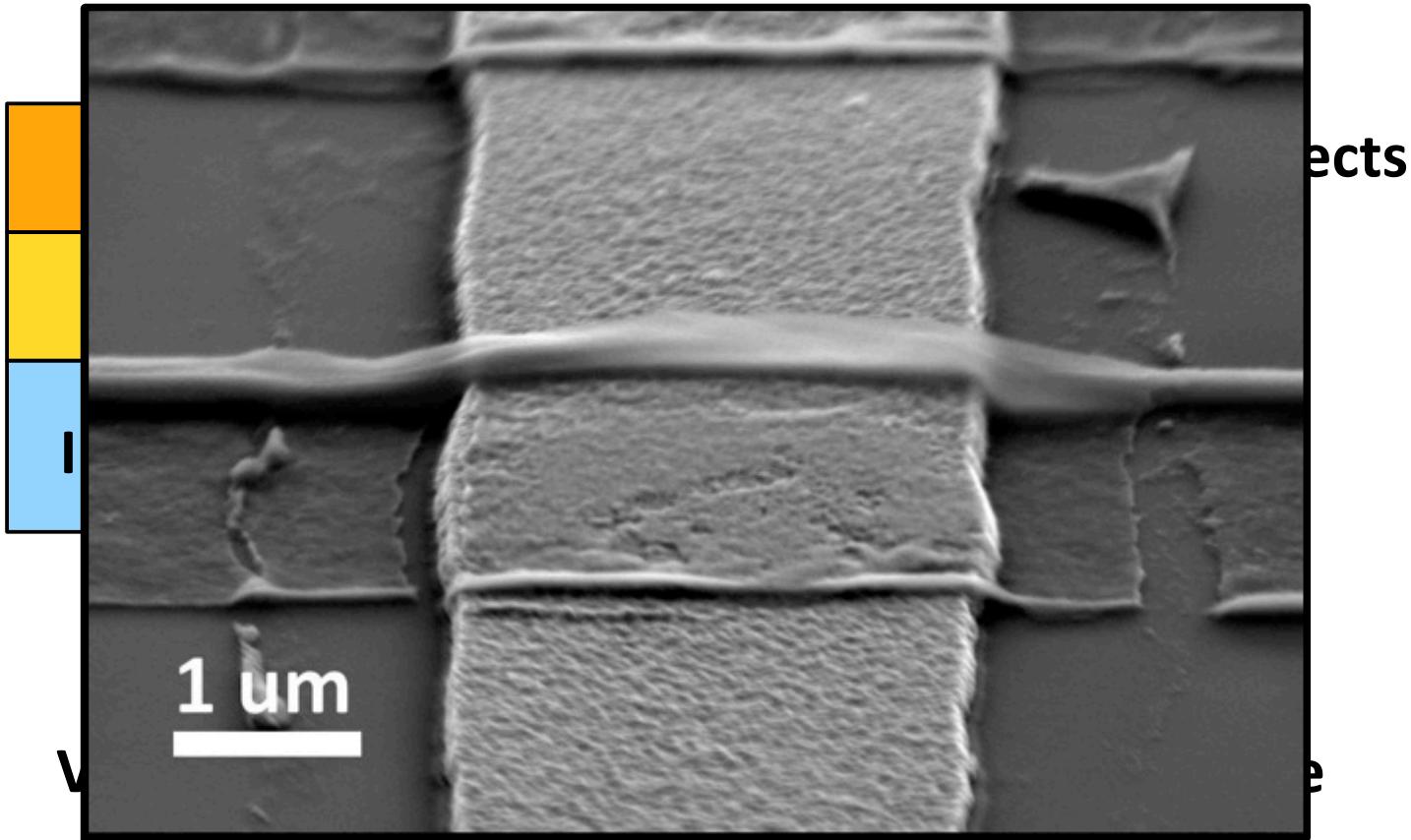


## Advantages

- very high on-off ratios
- can have very high operating frequencies
- can be used with loaded graphene for sensing applications
- robust in extreme environments

Kumar et al. unpublished

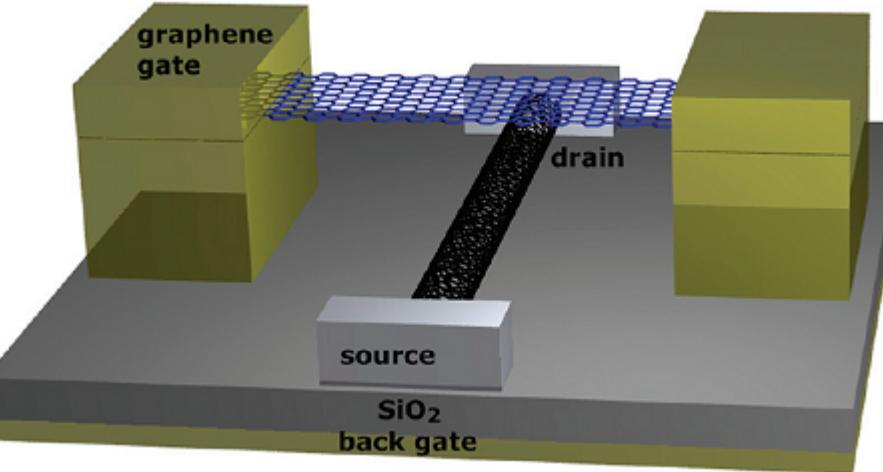
## Suspended graphene



Surface tension breaks G → use critical point dryer

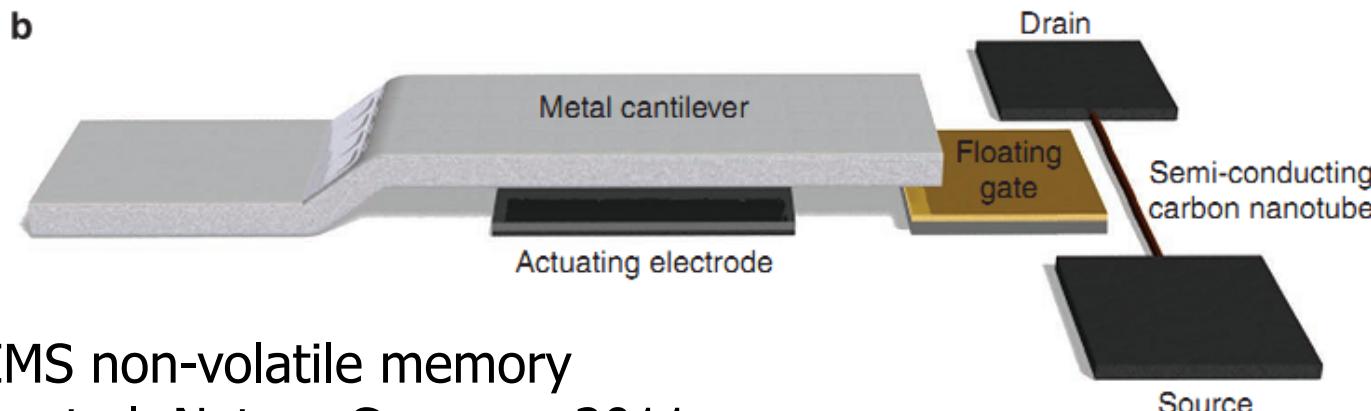


# Carbon NEMS devices



Overcome Subthreshold limit

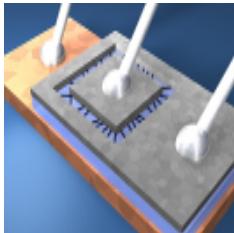
Moving gate,  
Svenson et al. Nanoletters 2011



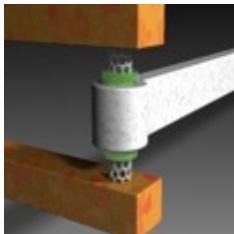
NEMS non-volatile memory  
Lee et al. Nature Commun 2011



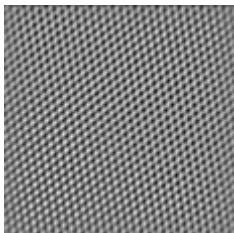
# Conclusions



Lateral carbon FETs may have application as power transistors or in flexible, transparent electronics, sensors etc. (More than Moore)



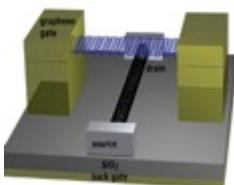
Vertical FET face integration challenges (high  $k$ , contact engineering, Growth of CNTs) but have a lot of potential



Graphene can be synthesized and processed on the large scale but band gap engineering/passivation is crucial – potential for Spintronics and NEMS



New 2D Materials have a lot of potential for electronics and energy harvesting



Carbon NEMS have superior properties



# Acknowledgements



## Collaborators

Prof G.T Kim – Korea University

Prof. Coleman – TCD

Prof. Boland - TCD

**Group:** Shishir Kumar, Niall McEvoy, ChanYoung Yim, Gareth Keeley, Ehsan Rezvani, Hugo Nolan, Nikos Peltekis (now Intel) Anne Weidlich, Toby Halham, Chris Murray (Intel), Hye-Young Kim, Kangho Lee (KU)

**Support by** Science Foundation Ireland, Enterprise Ireland, Embark Initiative HEA, EU for Marie Curie, FP7 (Electrograph)

Intel Ireland LTD, Hewlett Packard, Infineon AG

G.S. Duesberg, Ireland Summerschool, Leixlip , 30<sup>th</sup> August, 2011

